

Micromachining optical waveguides using a femtosecond laser oscillator

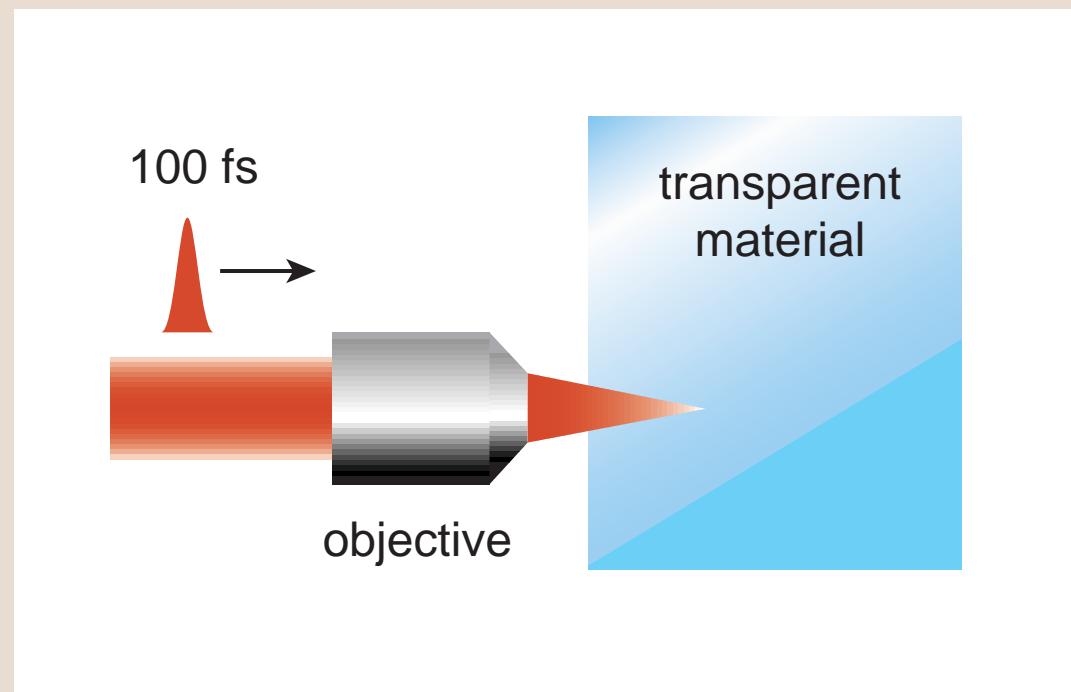
**Chris B. Schaffer
Jose F. Garcia
Alan Jamison
Eric Mazur**



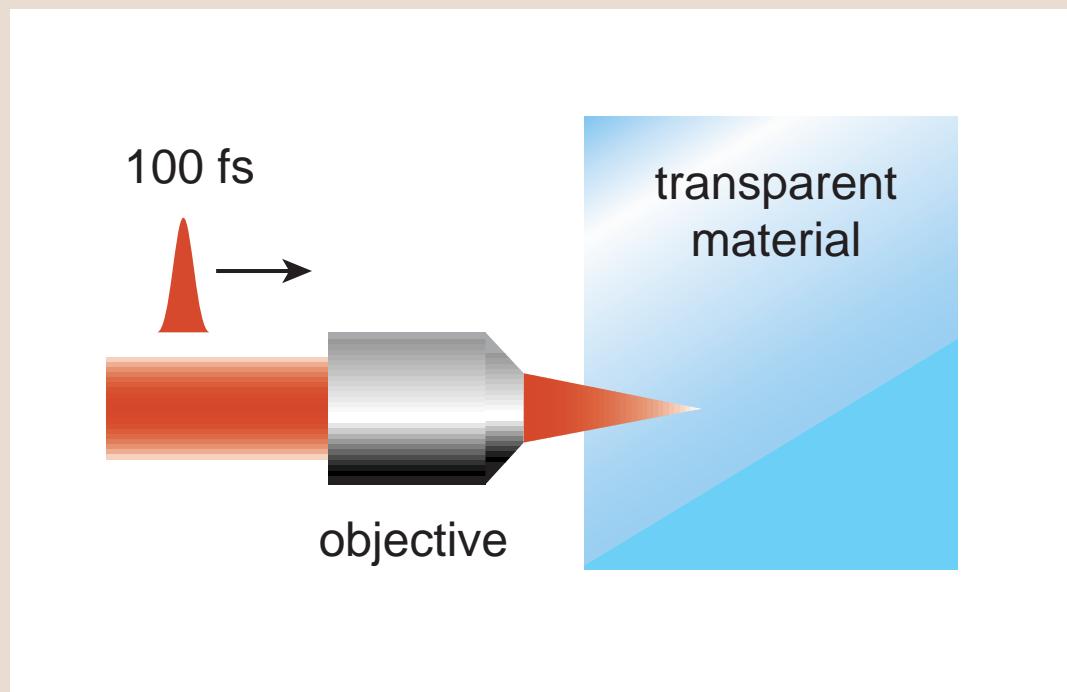
**OSA Annual Meeting
October, 2000**

**Harvard University
Department of Physics**

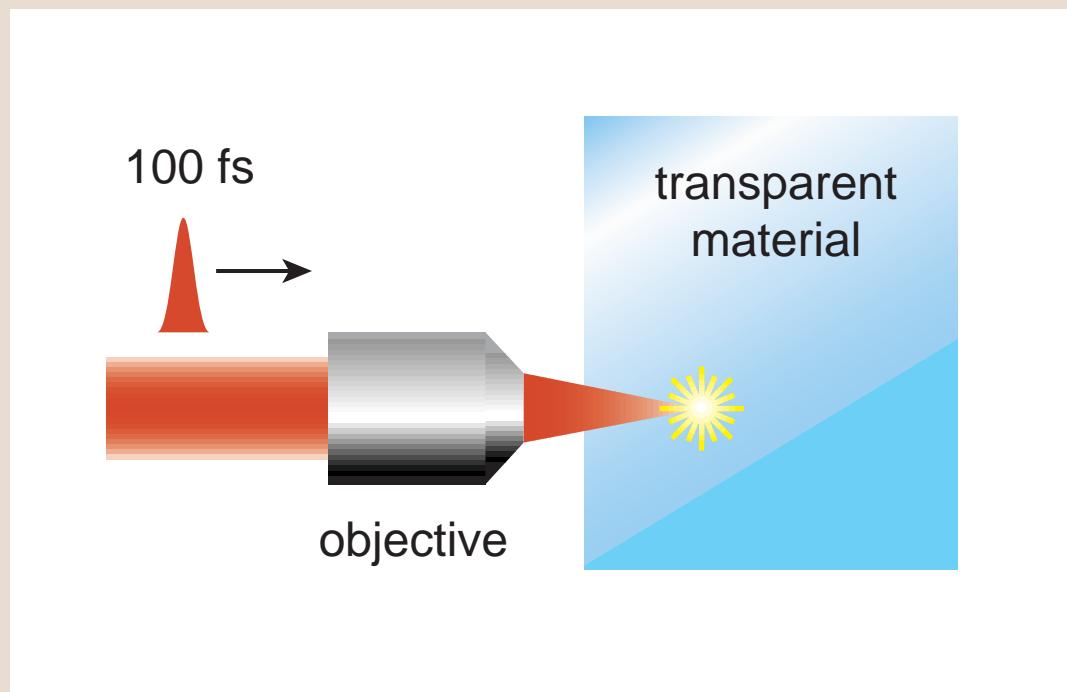
focus laser beam inside material



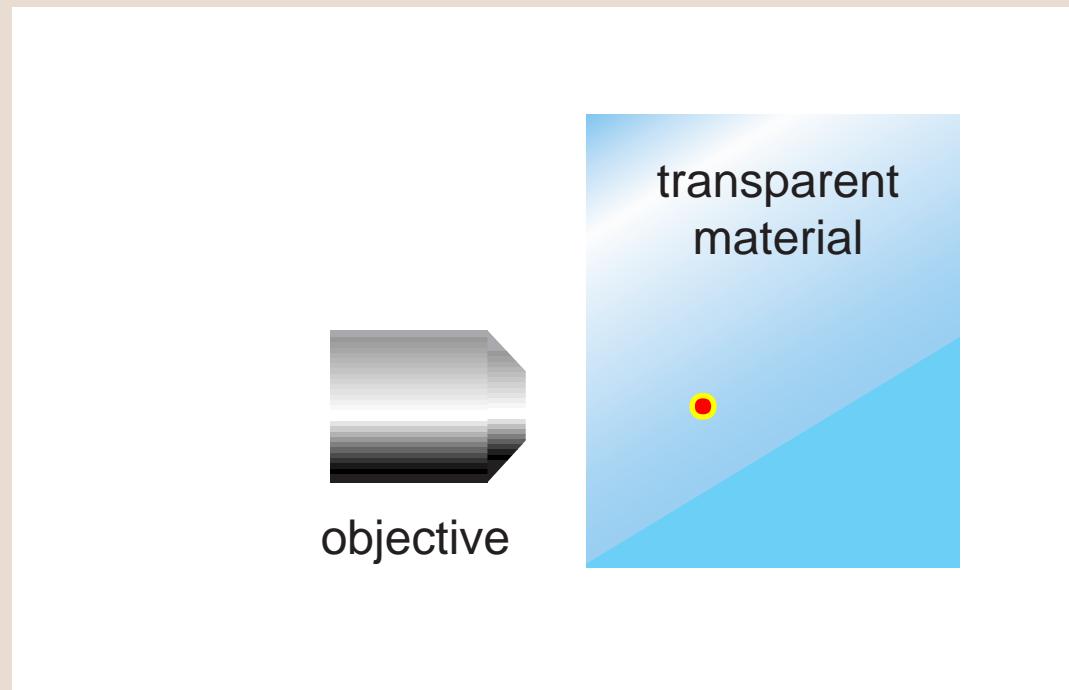
high intensity at focus



causes nonlinear ionization

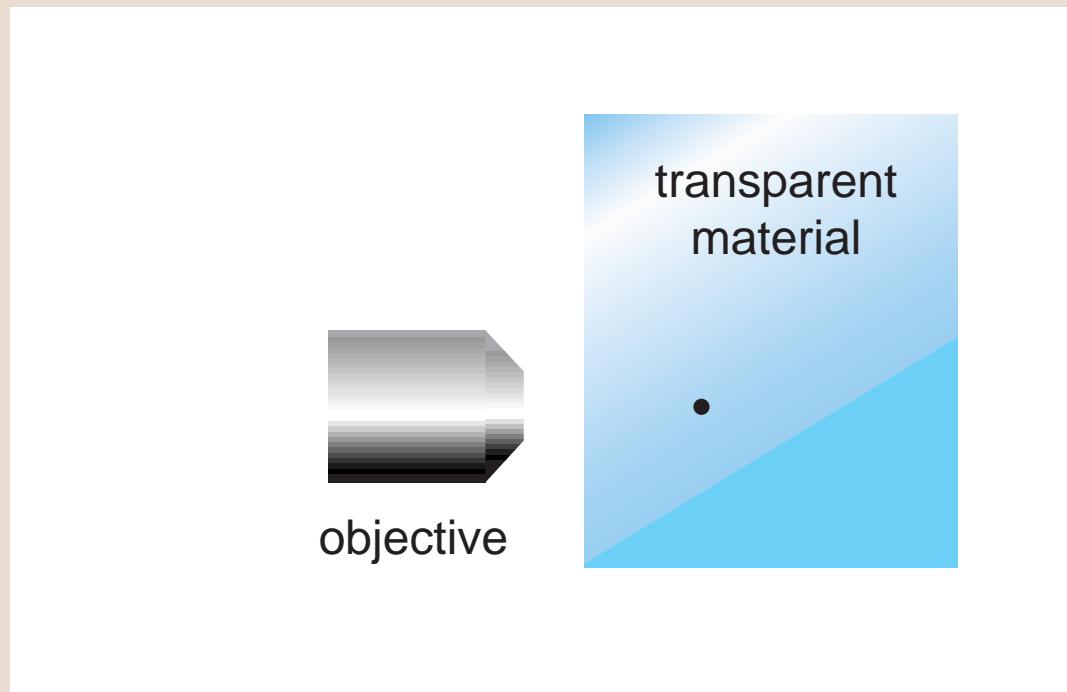


energy is deposited in the focal volume



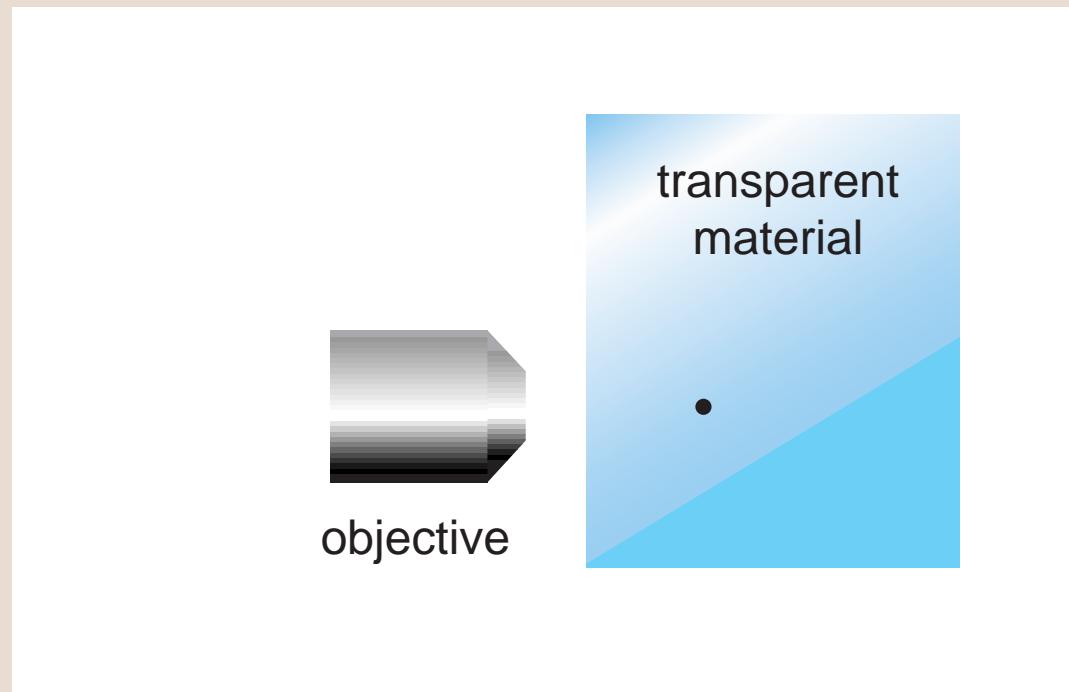
INTRODUCTION

producing microscopic bulk damage



INTRODUCTION

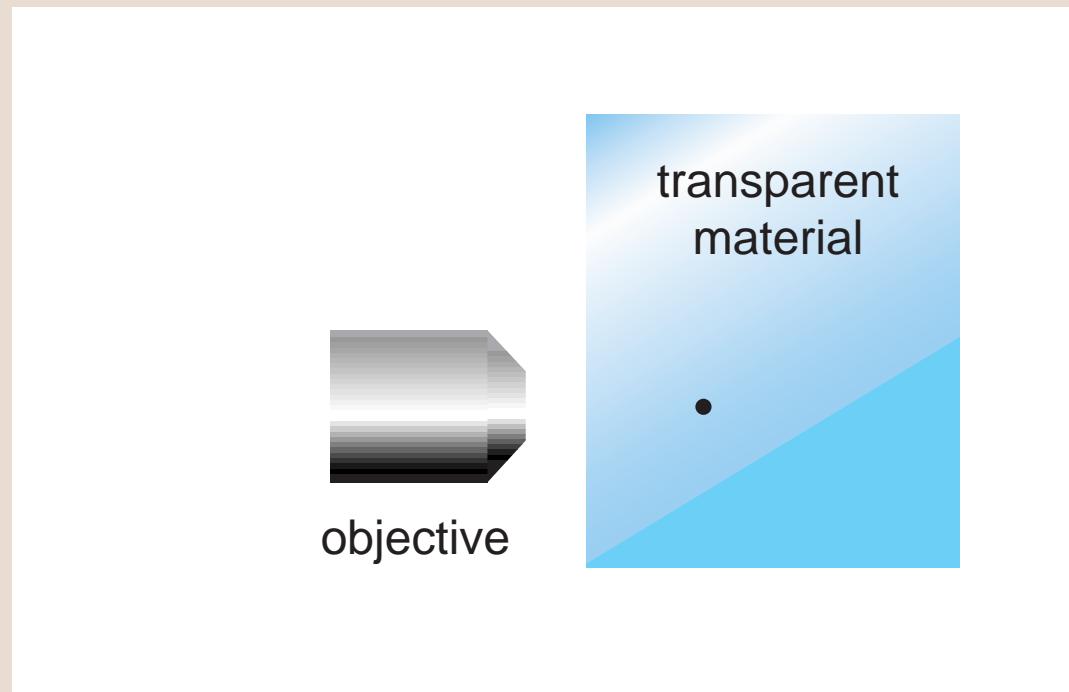
producing microscopic bulk damage



with only tens of nanojoules!

INTRODUCTION

producing microscopic **bulk** damage

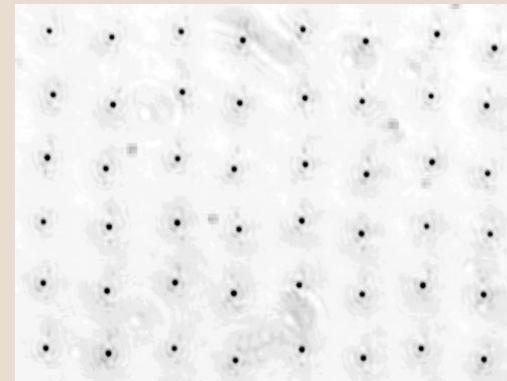


with only tens of **nanojoules**!

why bulk?

why bulk?

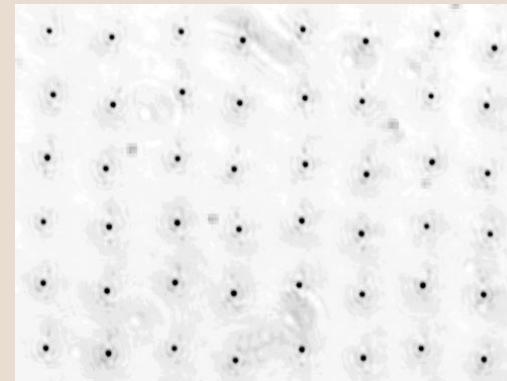
three-dimensional micromachining



INTRODUCTION

why bulk?

three-dimensional micromachining

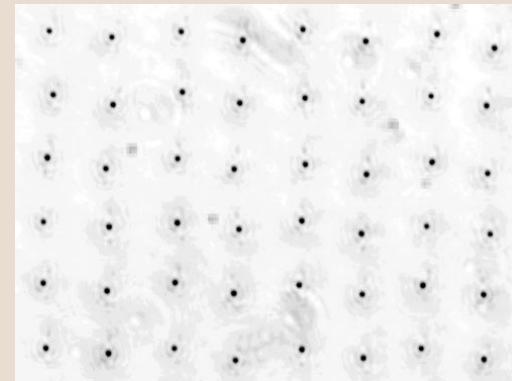


why nanojoules?

INTRODUCTION

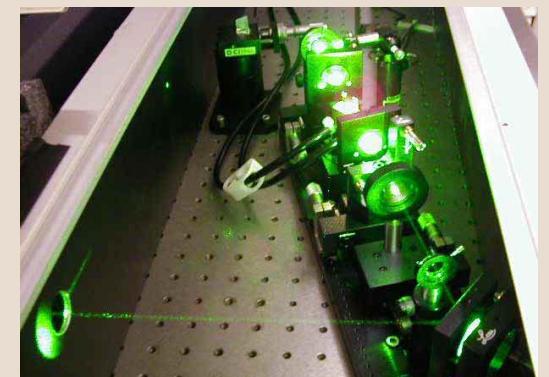
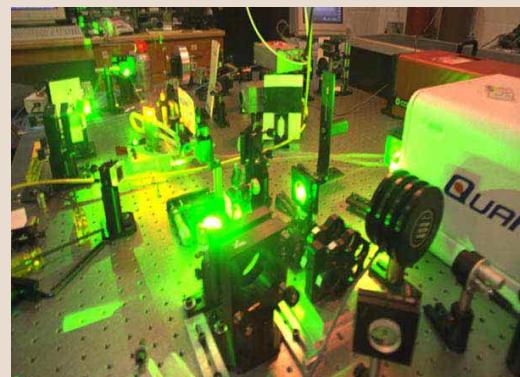
why **bulk?**

three-dimensional micromachining



why **nanojoules?**

non-amplified micromachining



3-D micromachining of photonics devices

structural change morphology

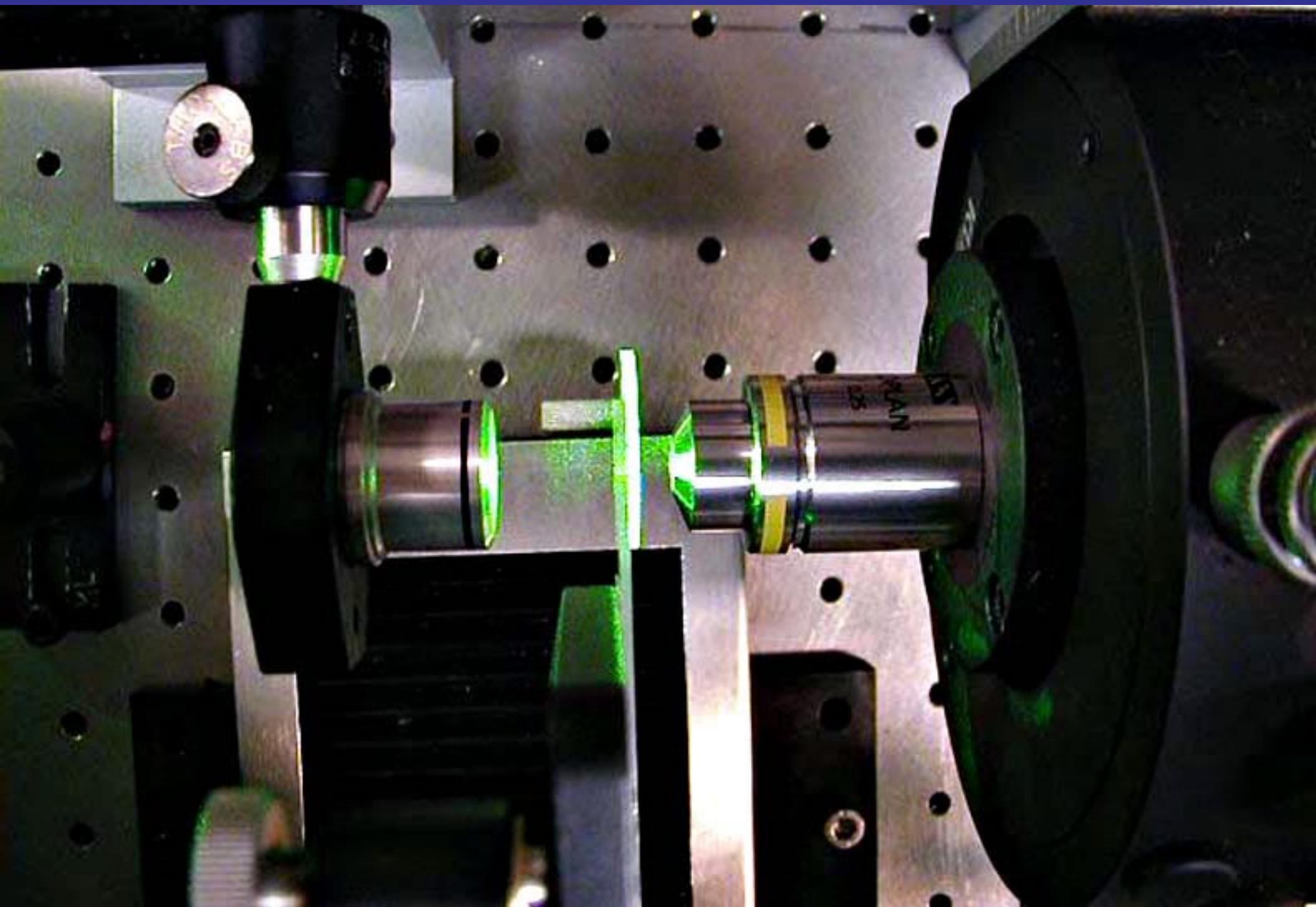
nonlinear ionization

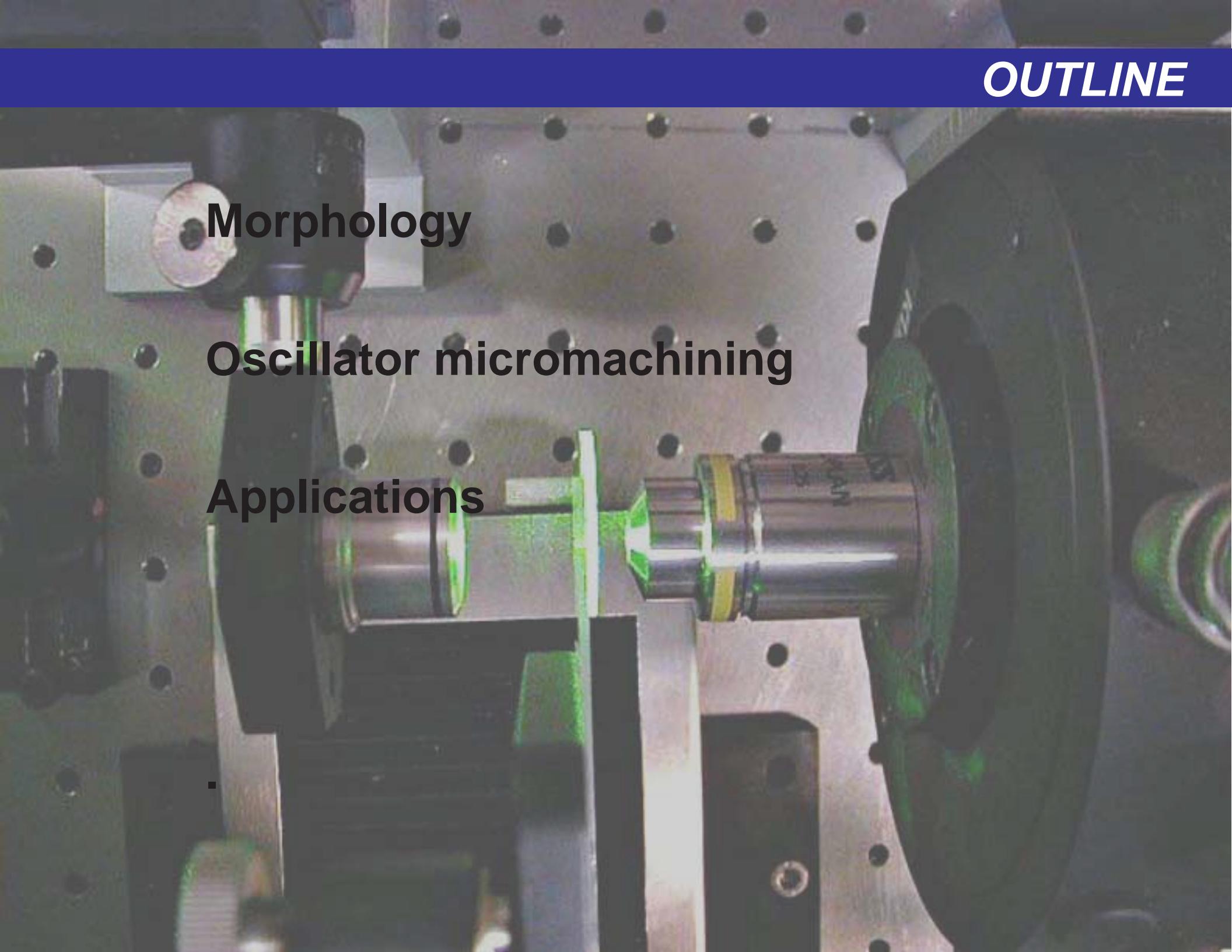
sub-cellular laser surgery

laser induced chemical changes

white light generation

OUTLINE



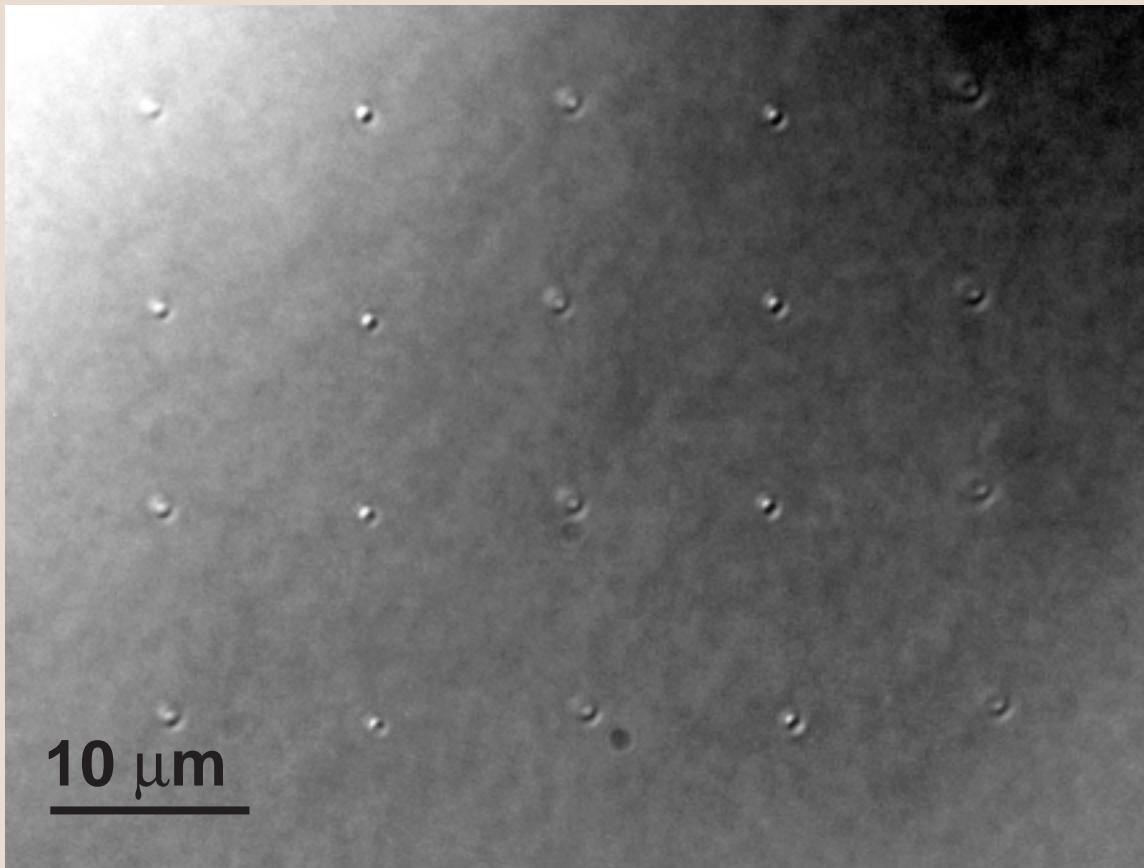


Morphology

Oscillator micromachining

Applications

MORPHOLOGY

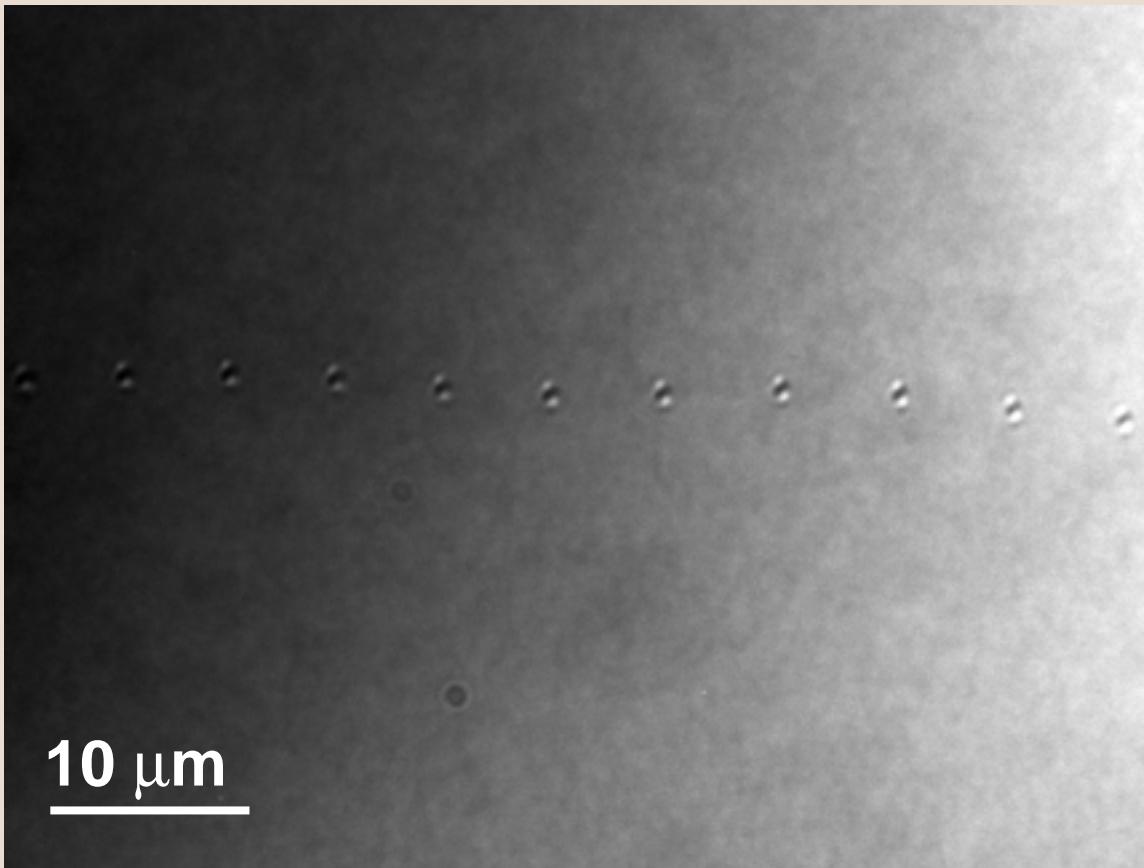


10 nJ
100 fs
1.4 NA
Corning 0211

\otimes^k

top view

MORPHOLOGY



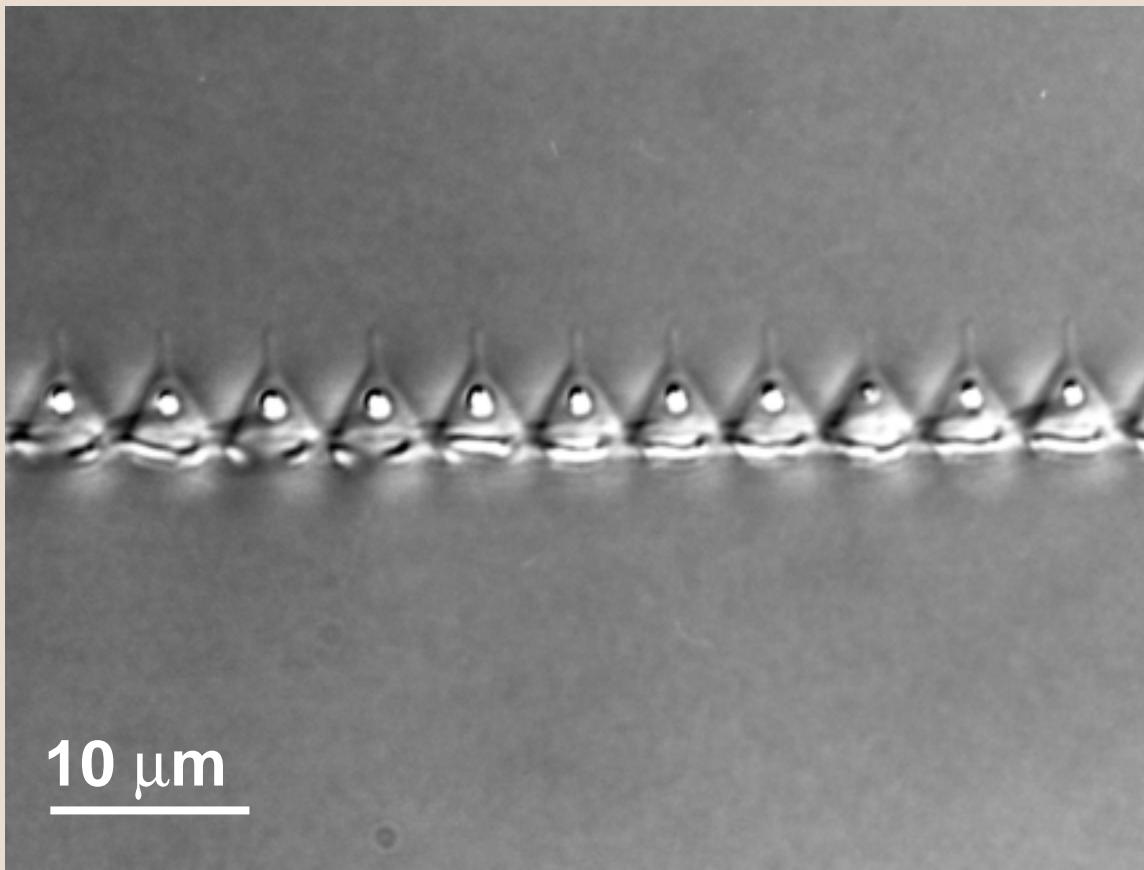
15 nJ
100 fs
1.4 NA
Corning 0211

10 μm

↑*k*

side view

MORPHOLOGY



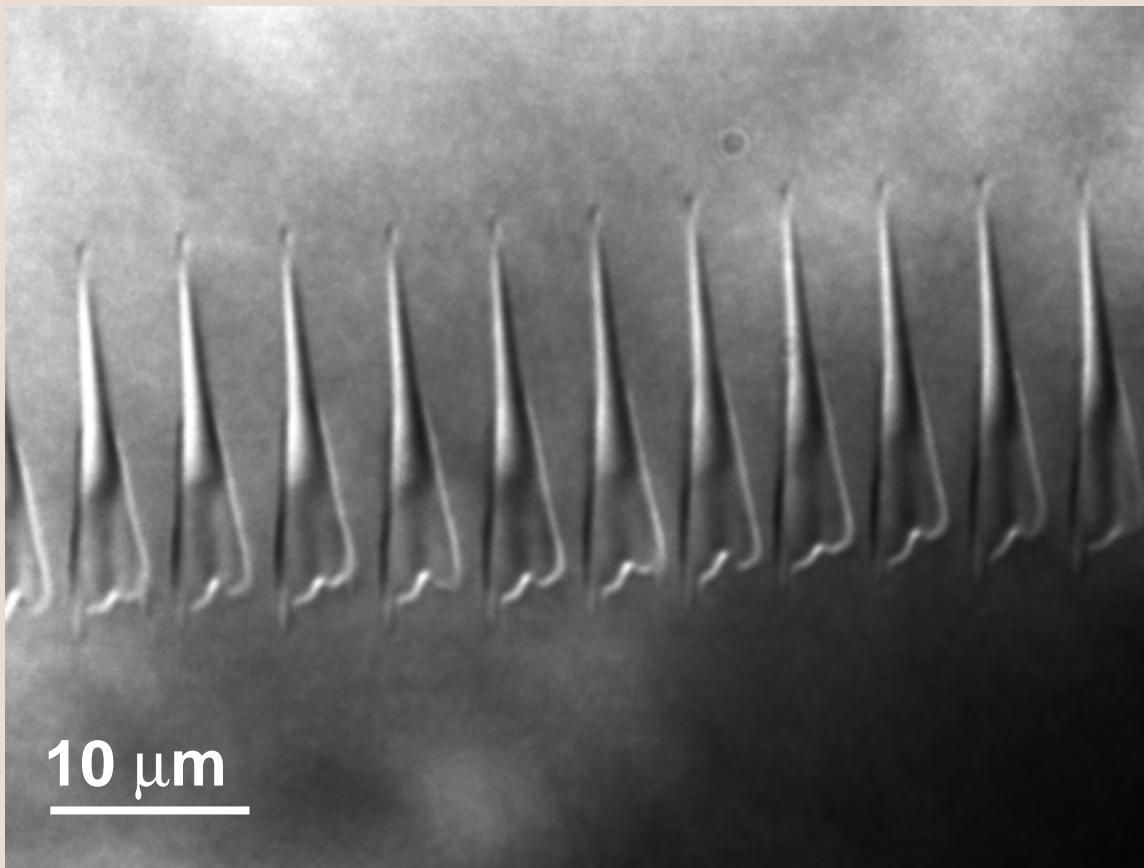
500 nJ
100 fs
1.4 NA
Corning 0211

10 μm

↑
k

higher pulse energy

MORPHOLOGY

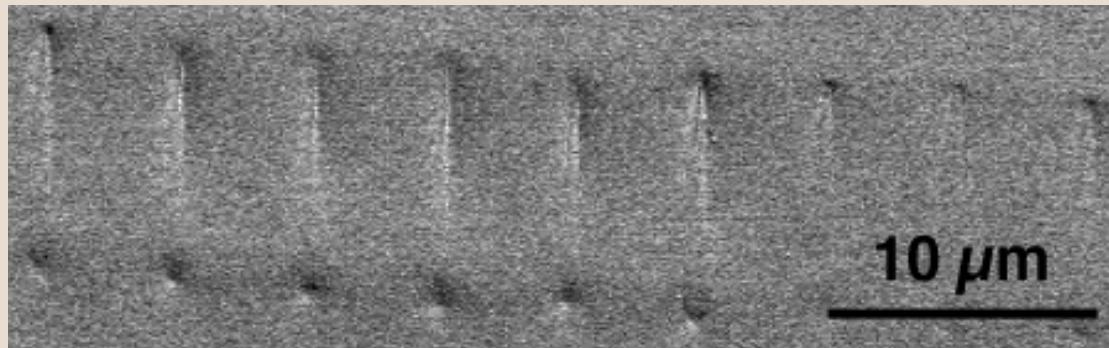


500 nJ
100 fs
0.45 NA
Corning 0211

↑
k

slower focusing

MORPHOLOGY



140 nJ

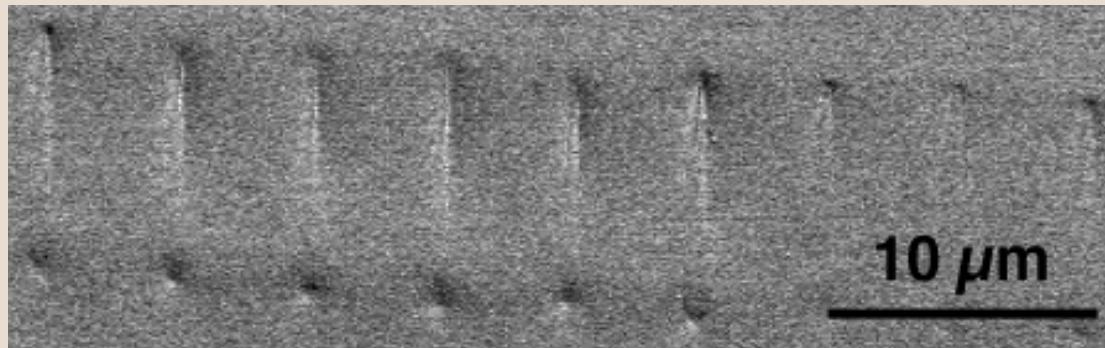
10 μm

100 fs
800 nm
0.45 NA
Corning 0211

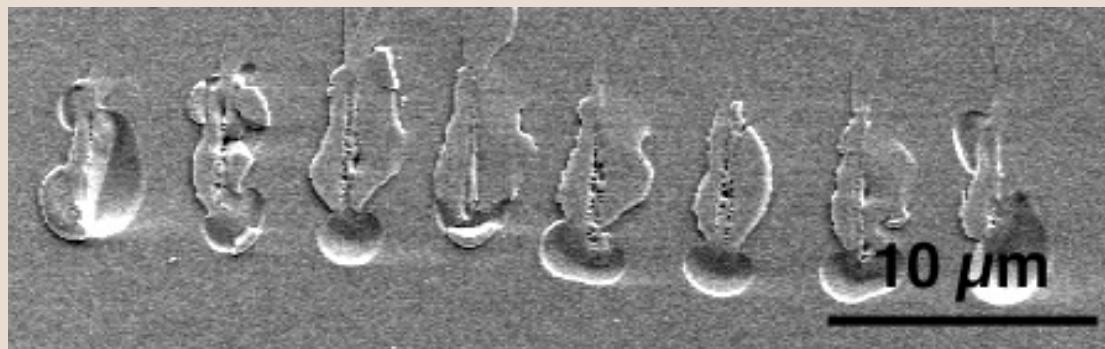
↑ k

side view SEM

MORPHOLOGY



140 nJ



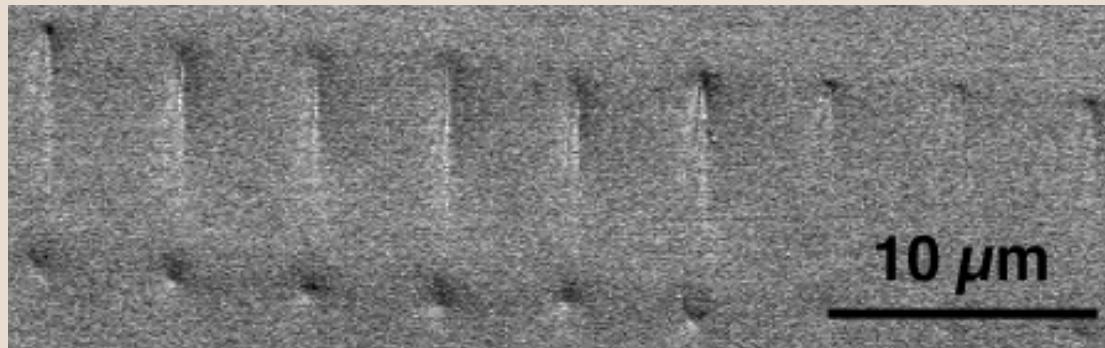
250 nJ

100 fs
800 nm
0.45 NA
Corning 0211

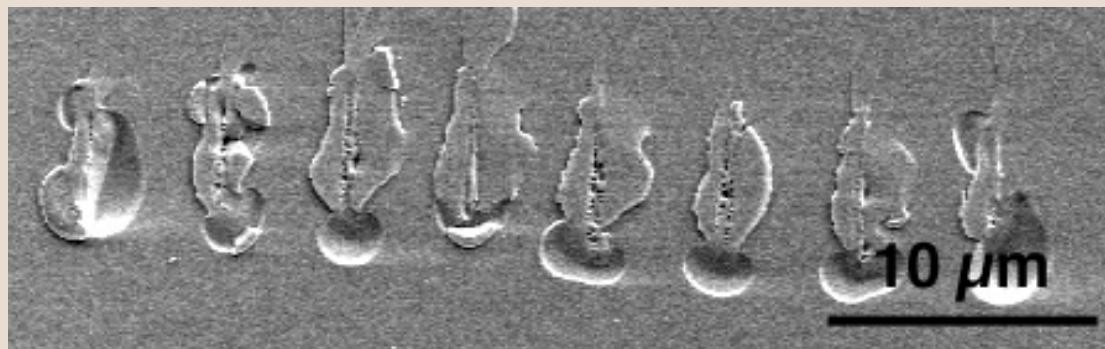
↑*k*

side view SEM

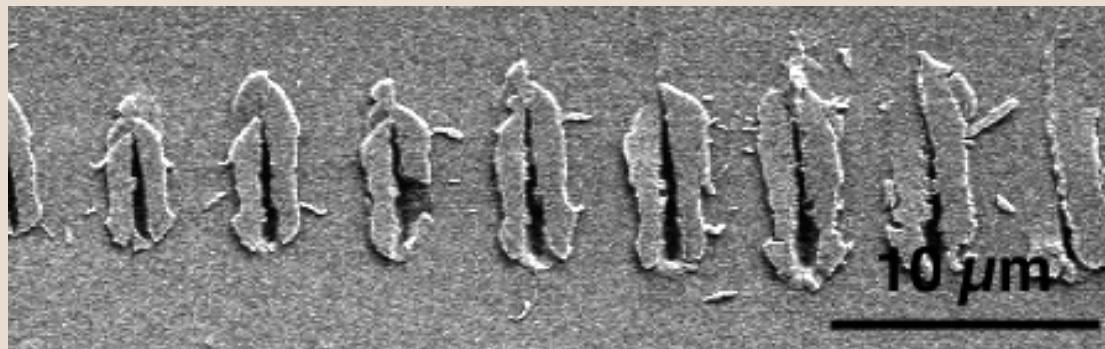
MORPHOLOGY



140 nJ



250 nJ

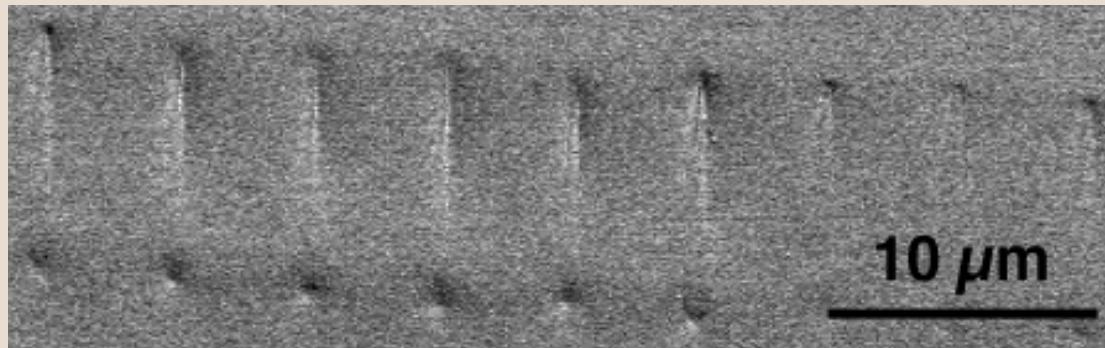


540 nJ
↑
k

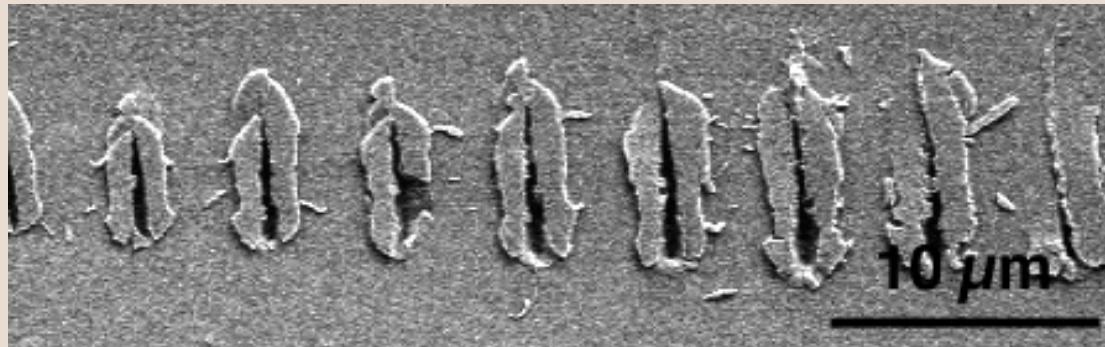
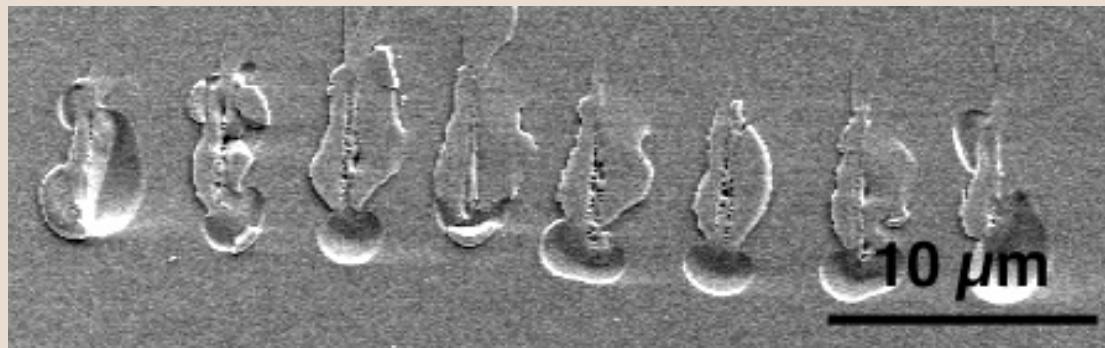
100 fs
800 nm
0.45 NA
Corning 0211

side view SEM

MORPHOLOGY



thermal
mechanism



explosive
mechanism

100 fs
800 nm
0.45 NA
Corning 0211

side view SEM

MORPHOLOGY

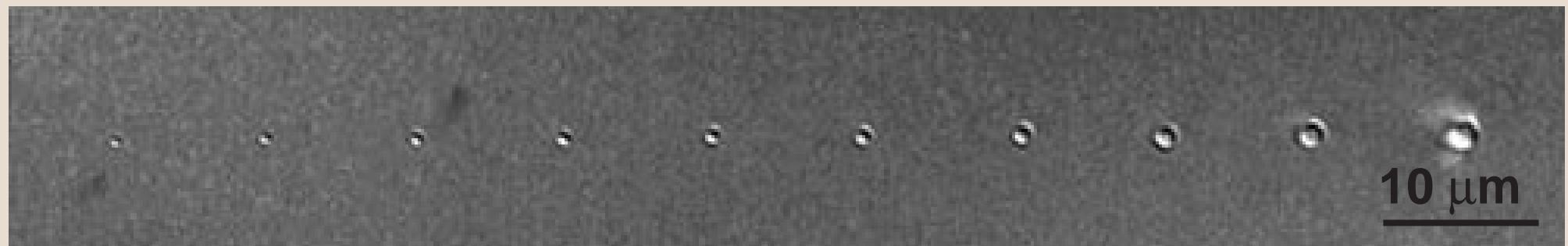
vary laser energy

6.6 nJ

13 nJ

33 nJ

66 nJ



100 fs
1.4 NA
Corning 0211

\otimes^k

MORPHOLOGY

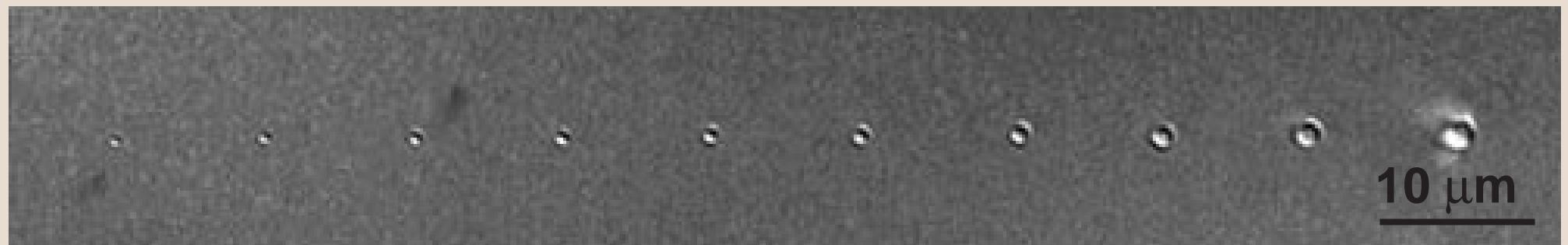
vary laser energy

6.6 nJ

13 nJ

33 nJ

66 nJ



100 fs
1.4 NA
Corning 0211

\otimes^k

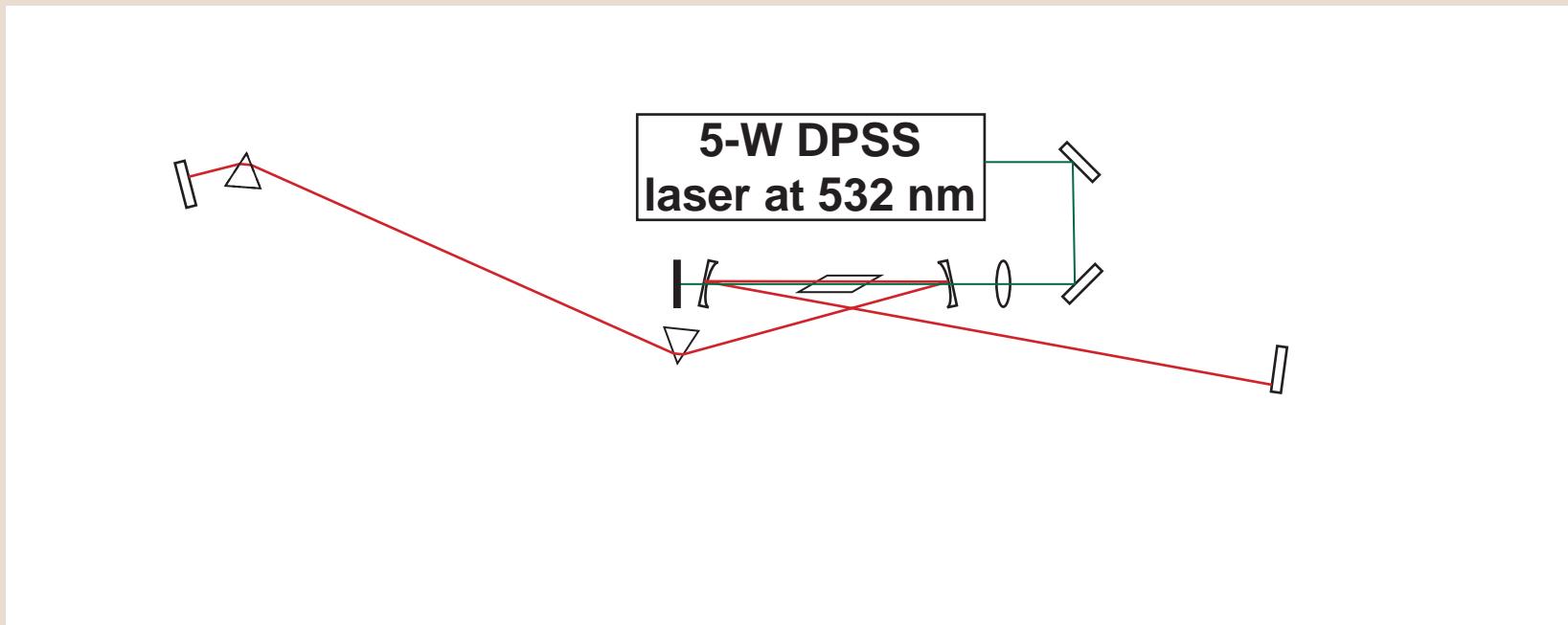
do we need amplified lasers to micromachine?

OSCILLATOR MICROMACHINING

**can we micromachine using only
a femtosecond laser oscillator?**

OSCILLATOR MICROMACHINING

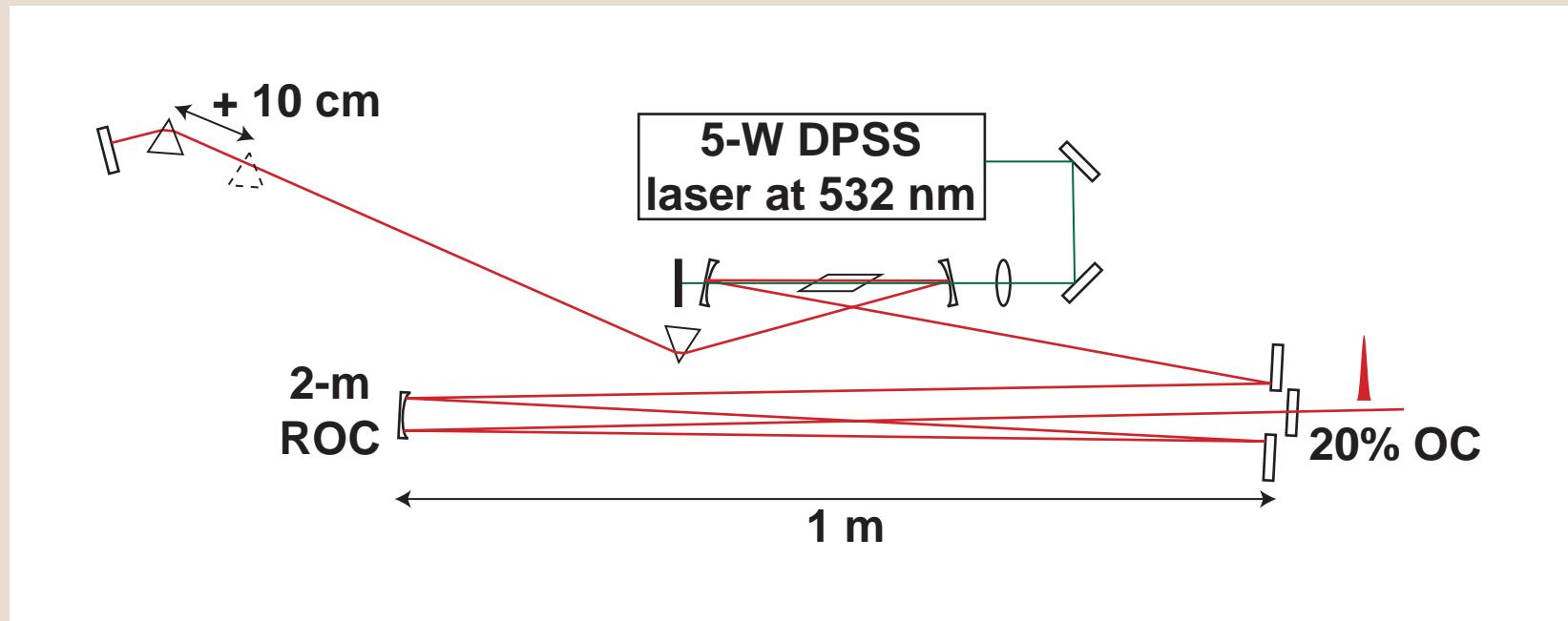
to deliver 5 nJ to the sample



after losses in the objective and prism compressor...

OSCILLATOR MICROMACHINING

... extend cavity of standard Ti:Sapph oscillator

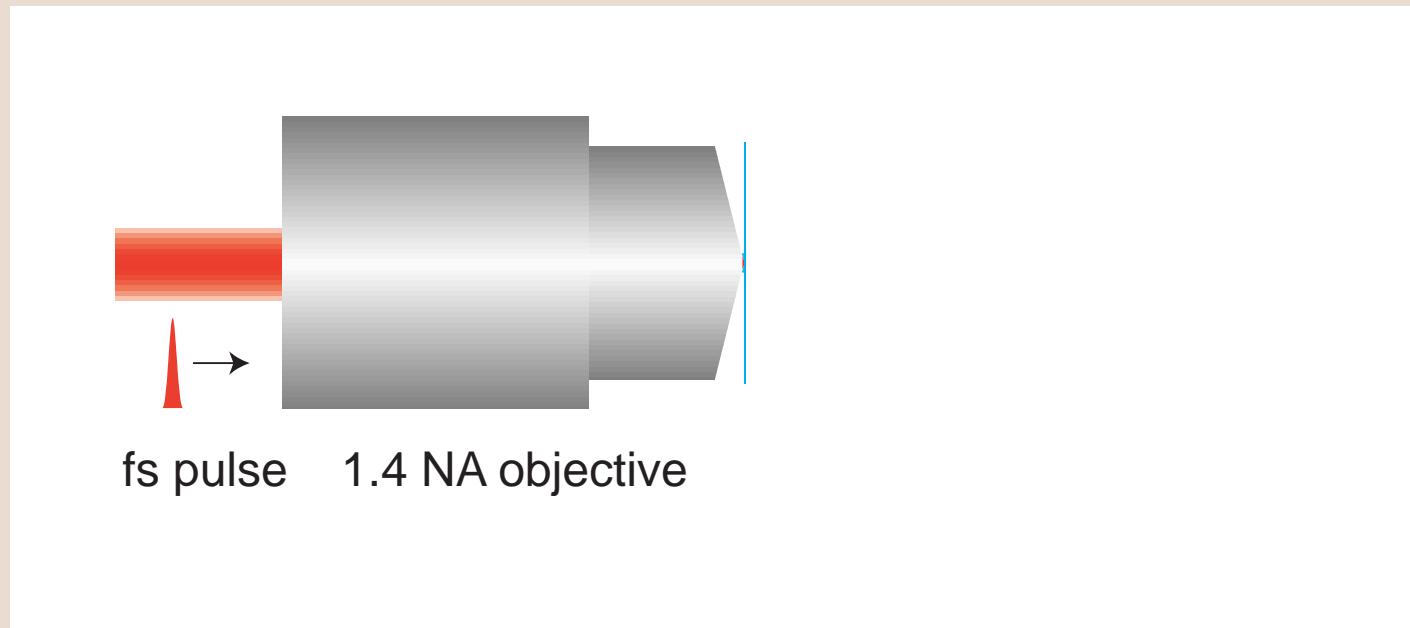


laser specs: 20 nJ, 25 MHz, 20 fs

Ref: A.R. Libertun, et.al., CLEO 1999; S.H. Cho, et. al., CLEO 1999.

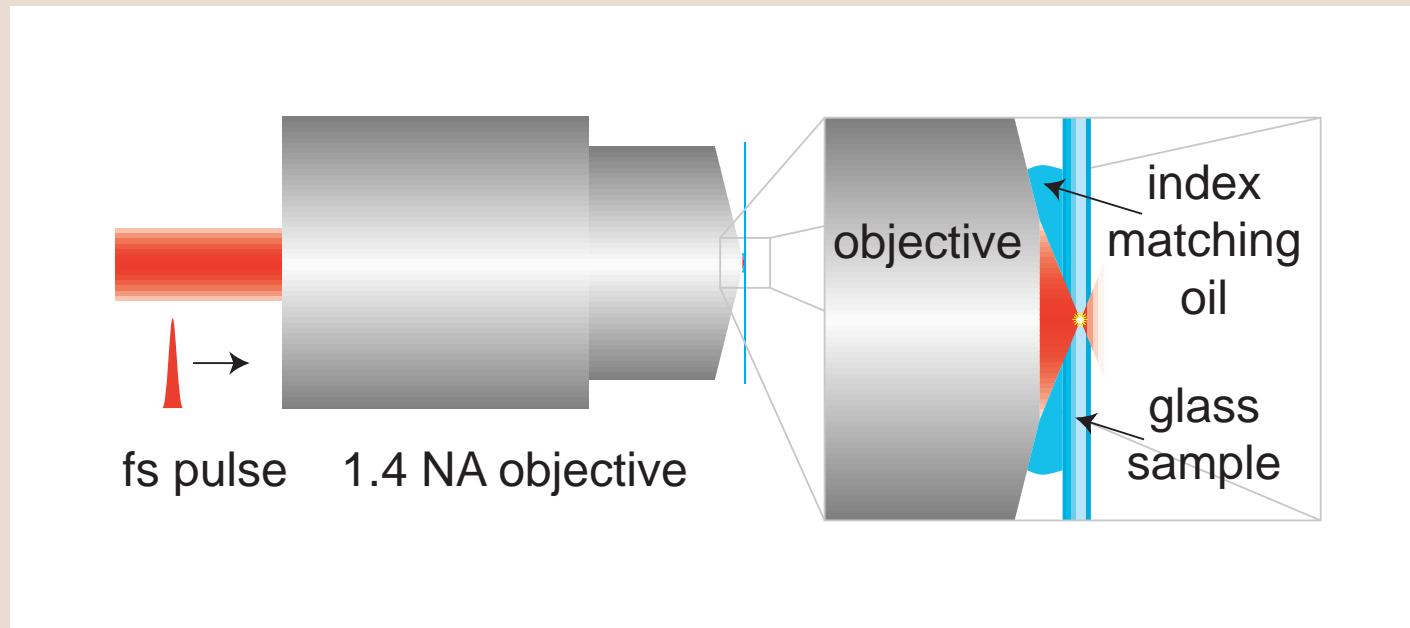
OSCILLATOR MICROMACHINING

scale model of 1.4 NA focusing geometry



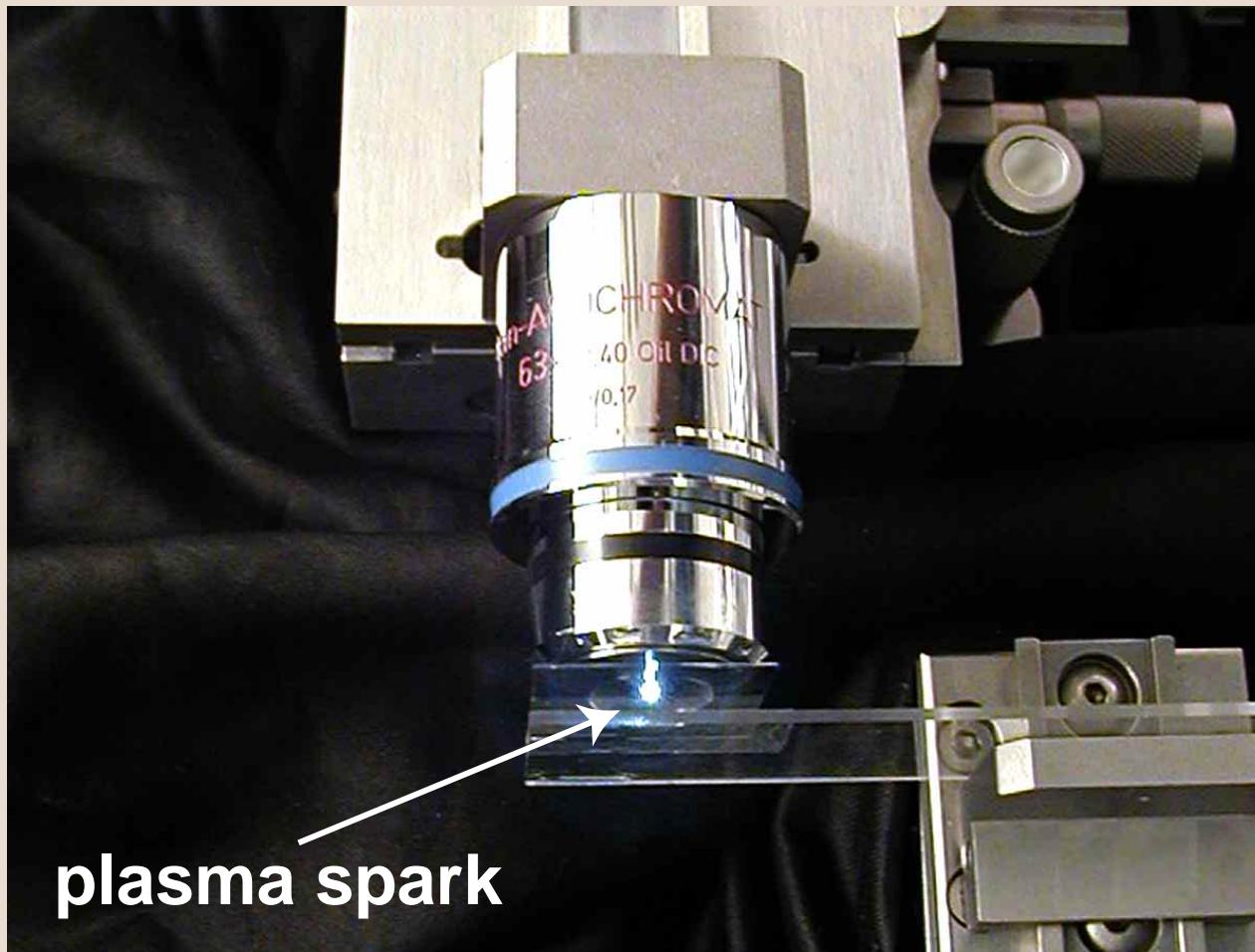
OSCILLATOR MICROMACHINING

scale model of 1.4 NA focusing geometry



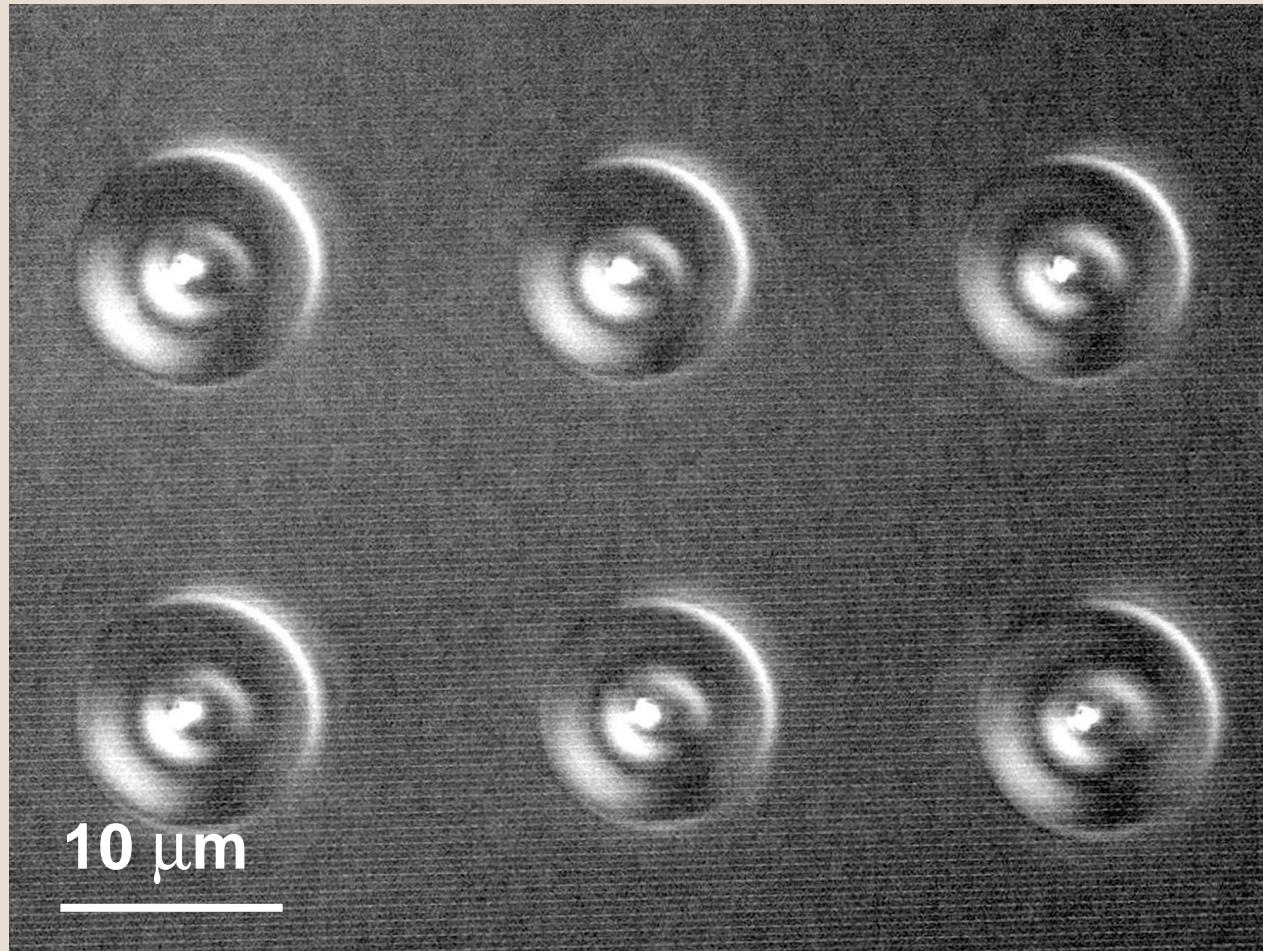
OSCILLATOR MICROMACHINING

actual 1.4 NA focusing geometry



OSCILLATOR MICROMACHINING

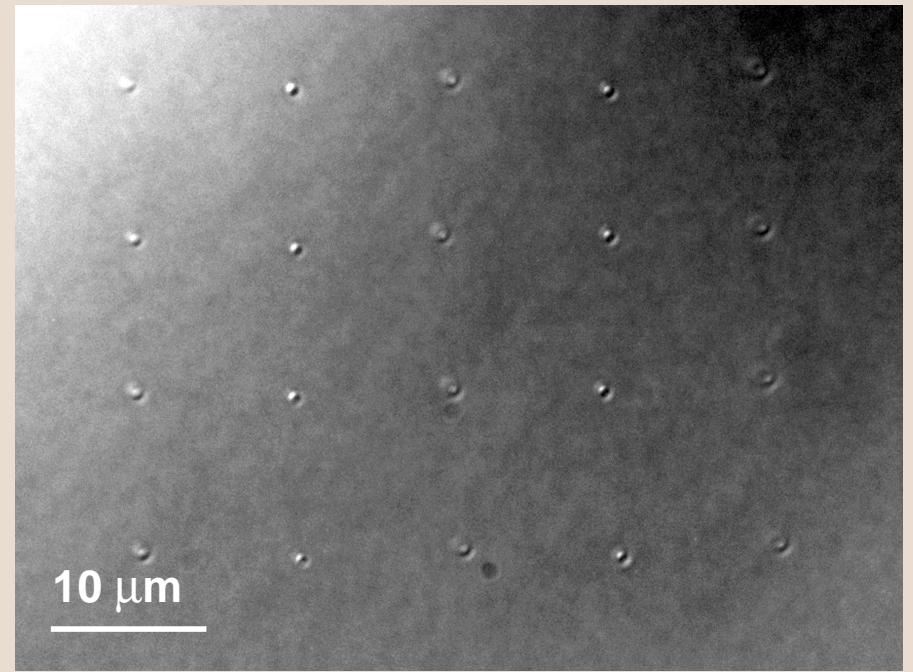
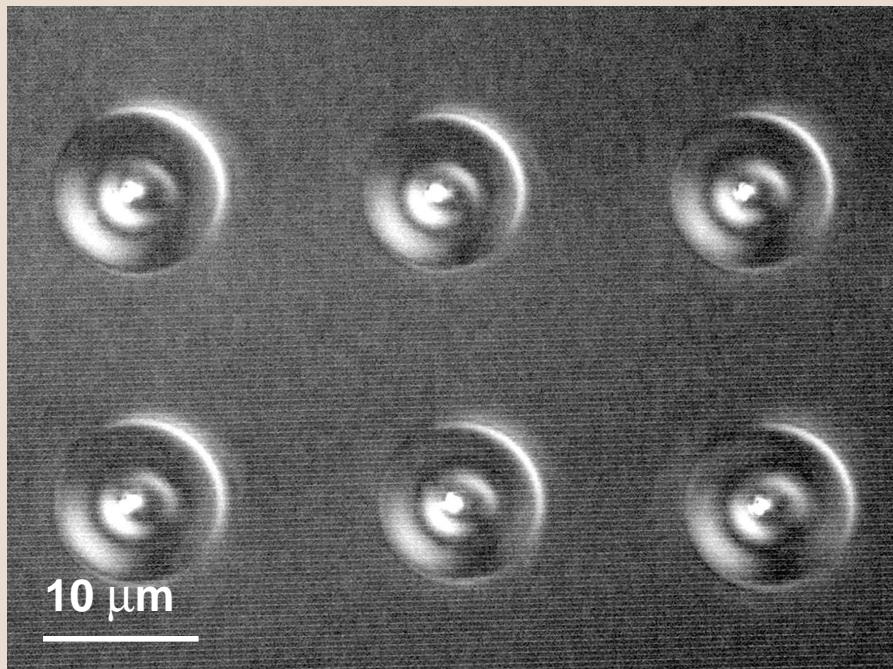
structures made with 25-MHz oscillator: 5 nJ; 25,000 shots



< 100 fs
800 nm
1.4 NA
Corning 0211

OSCILLATOR MICROMACHINING

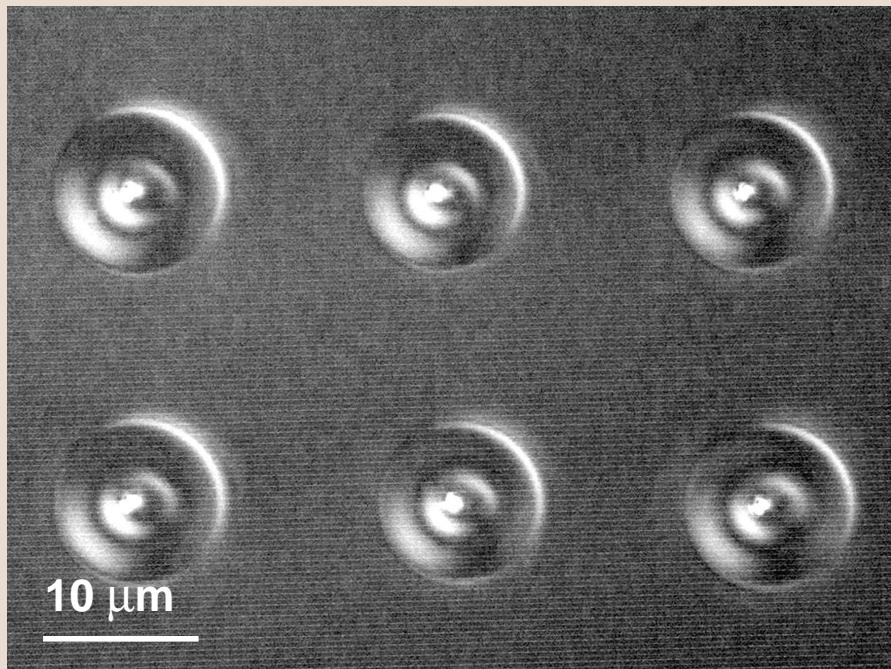
5 nJ; 25,000 shots



10 nJ; single shot

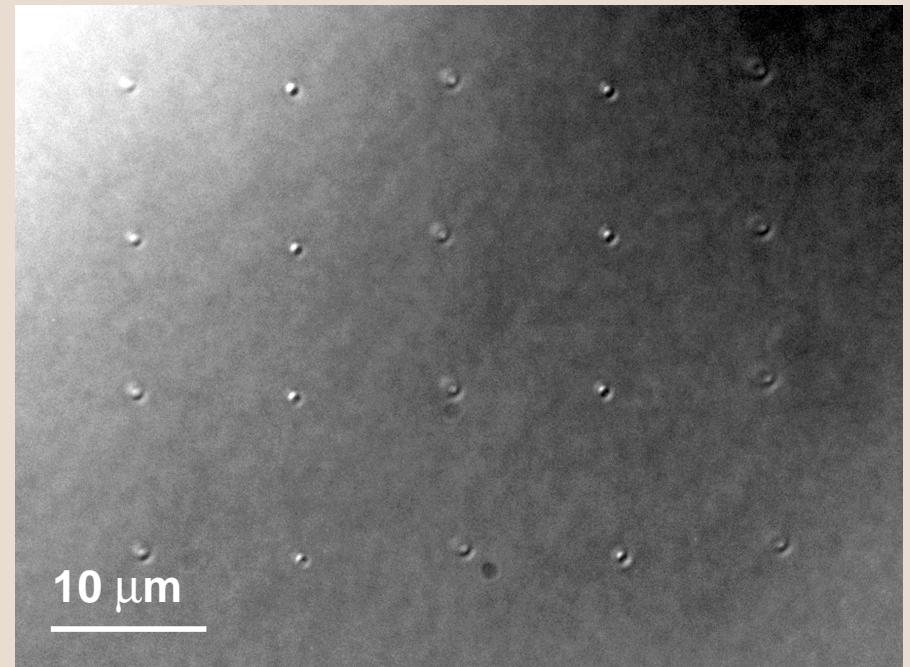
OSCILLATOR MICROMACHINING

5 nJ; 25,000 shots



**cumulative heating by
successive pulses melts
the glass**

**explosive or small-scale
melting mechanism**



10 nJ; single shot

OSCILLATOR MICROMACHINING

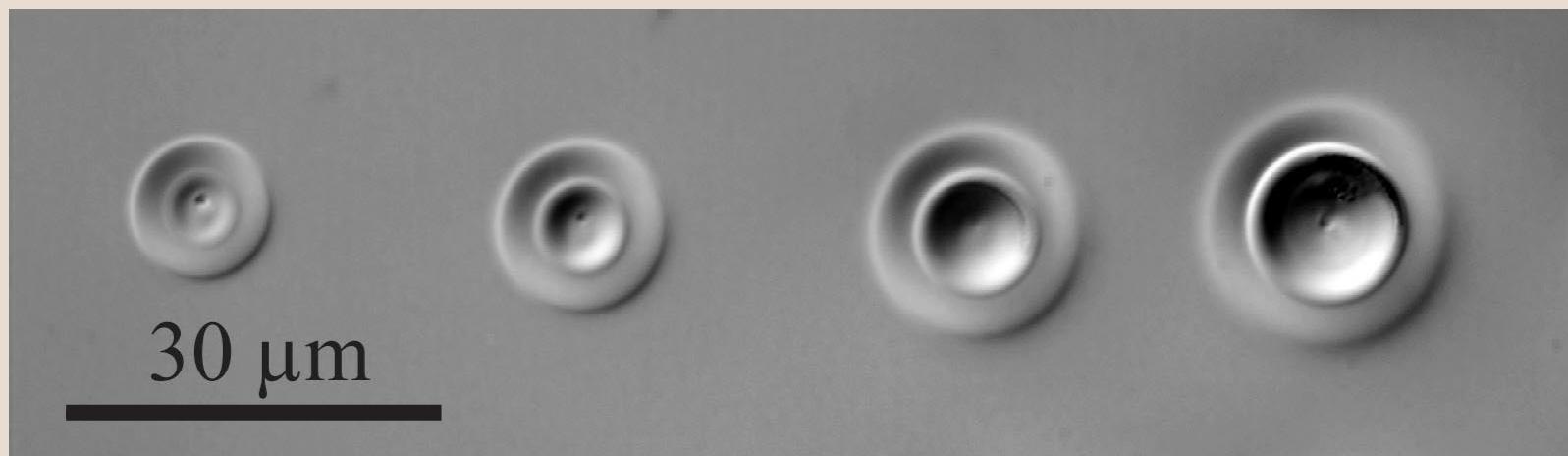
number of laser shots

2.5×10^4

2.5×10^5

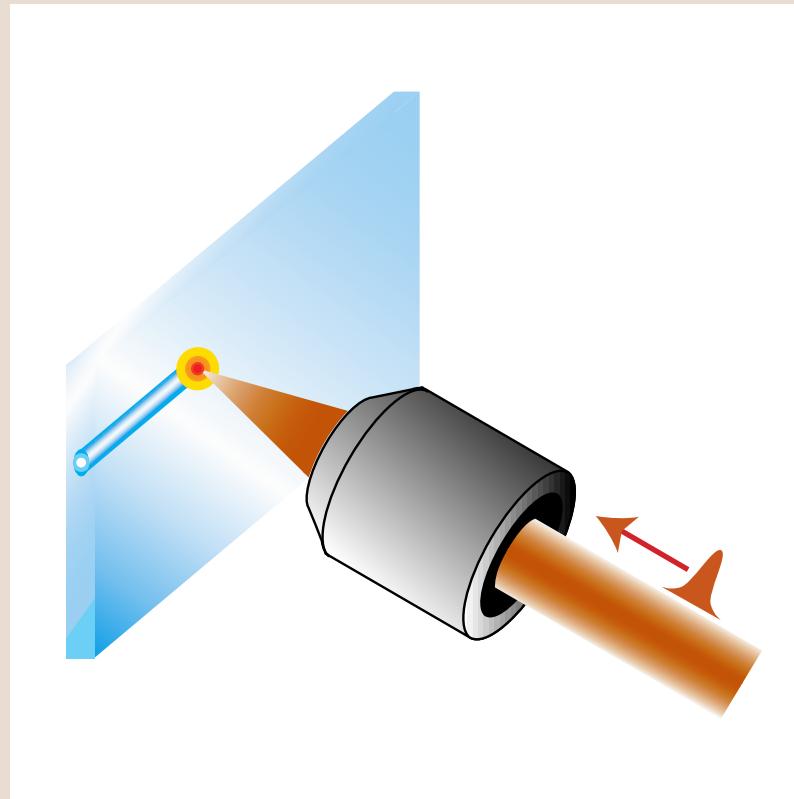
2.5×10^6

2.5×10^7



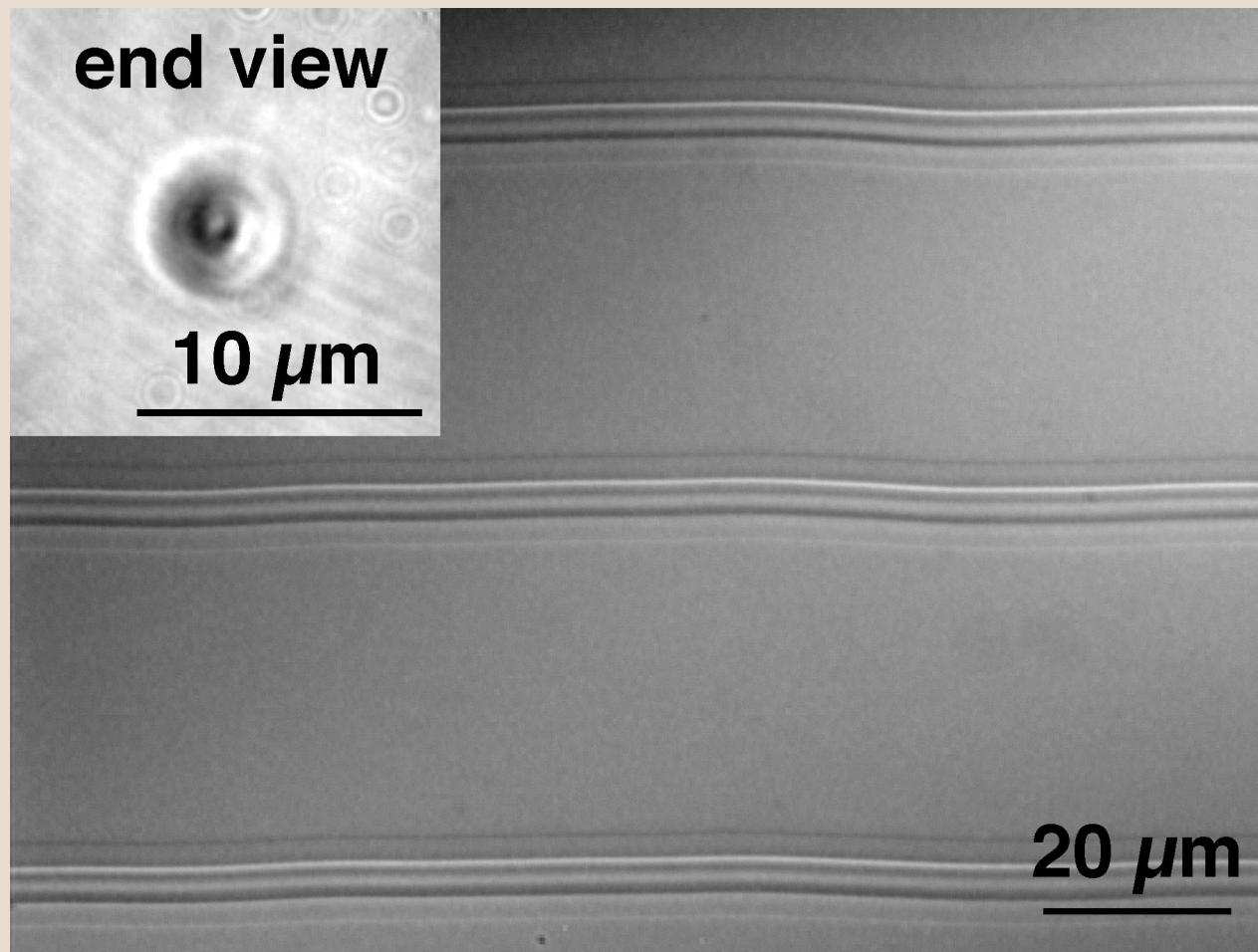
more shots melt larger volumes

how can we use femtosecond thermal micromachining?



write waveguides!

waveguide morphology: 20 mm/s machining speed



waveguide mode analysis

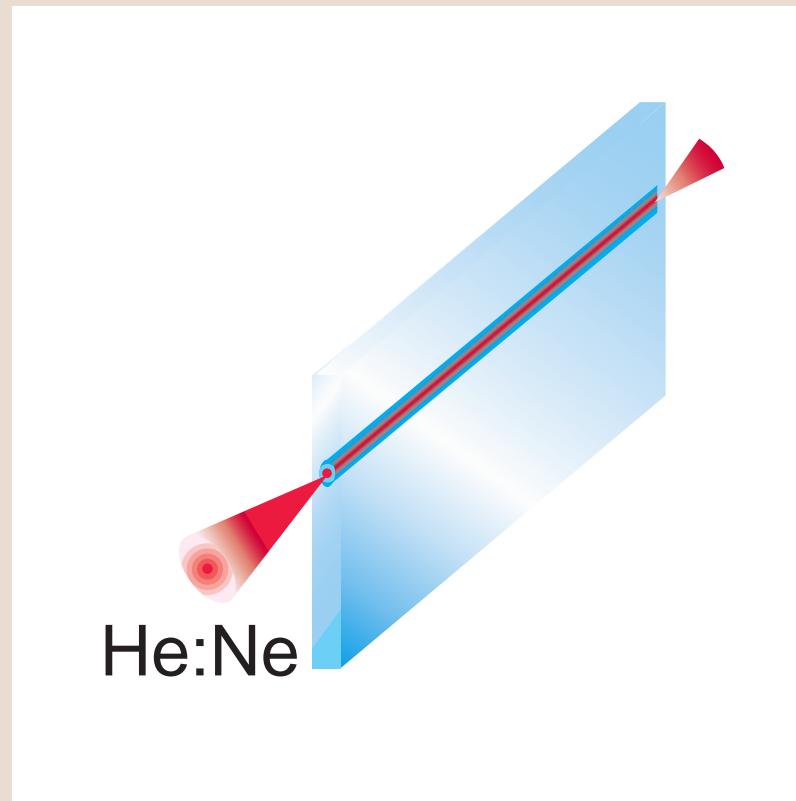
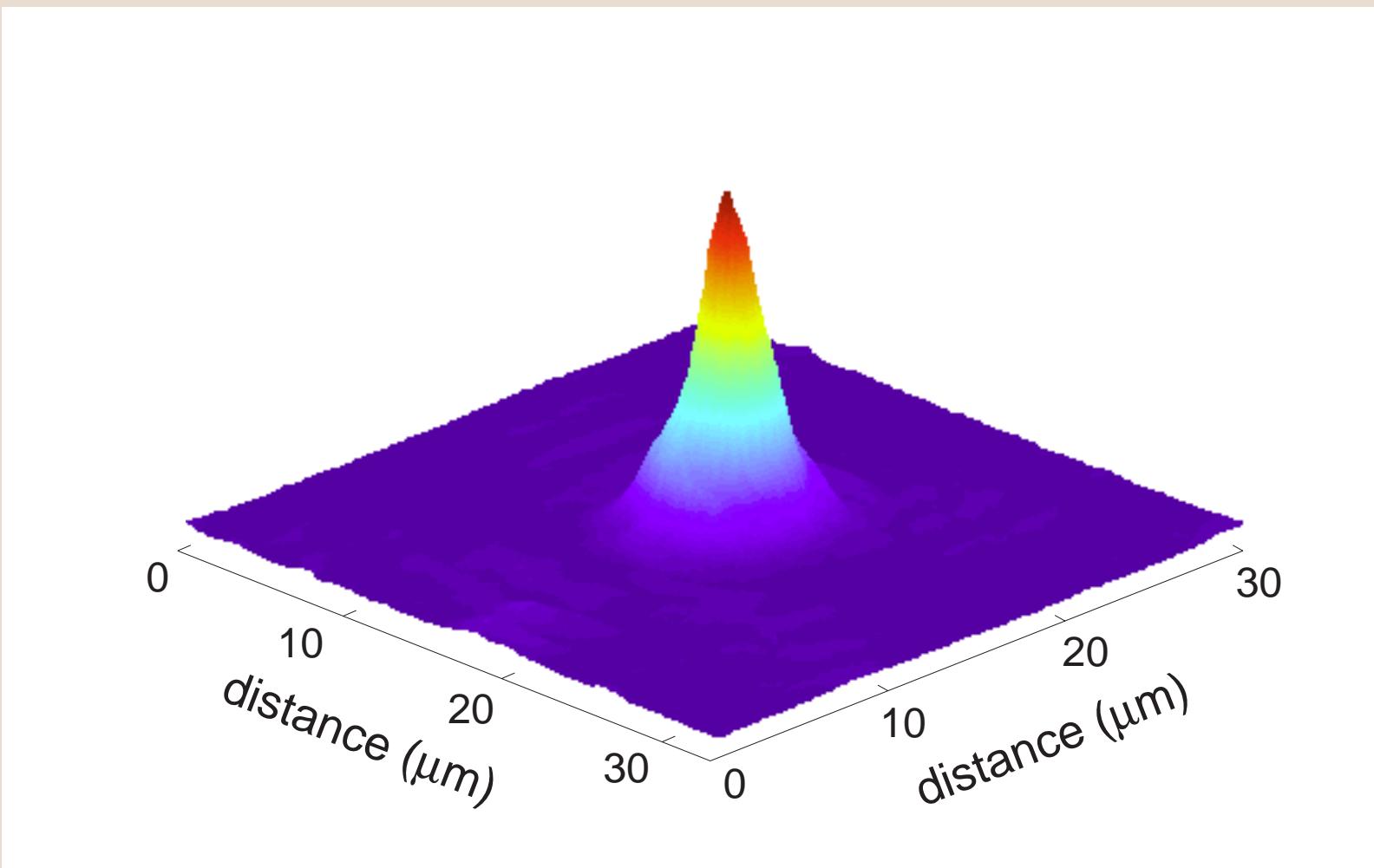
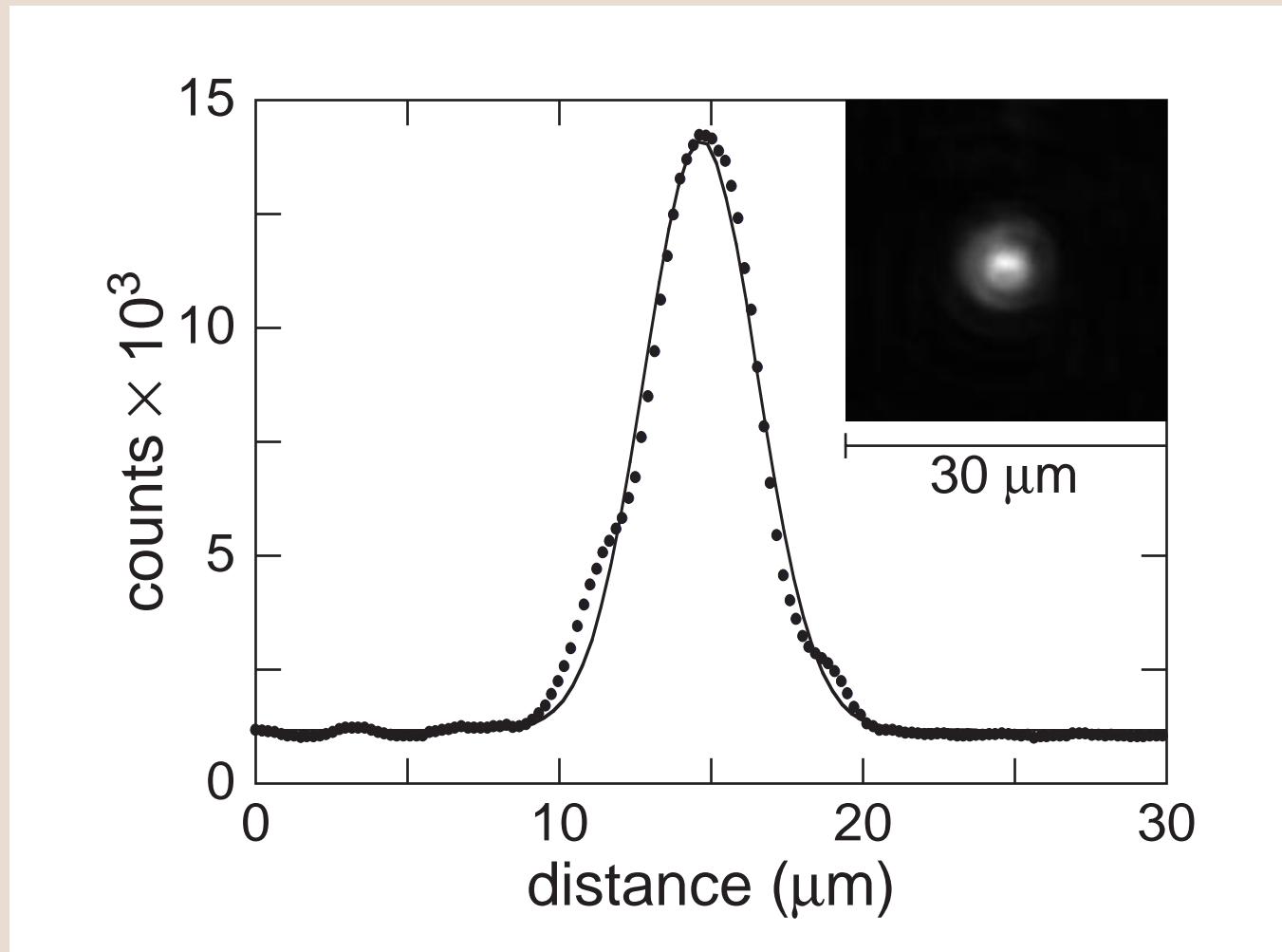


image of near field mode





line-out of near field waveguide mode for 633 nm

Morphology

- Connecting morphology to mechanisms

morphologies and mechanisms

	low energy	high energy
single shot	sub- μm Δn small melt	sub- μm voids explosive
multiple shot high rep. rate	μm -sized Δn cumulative melting	???

Morphology

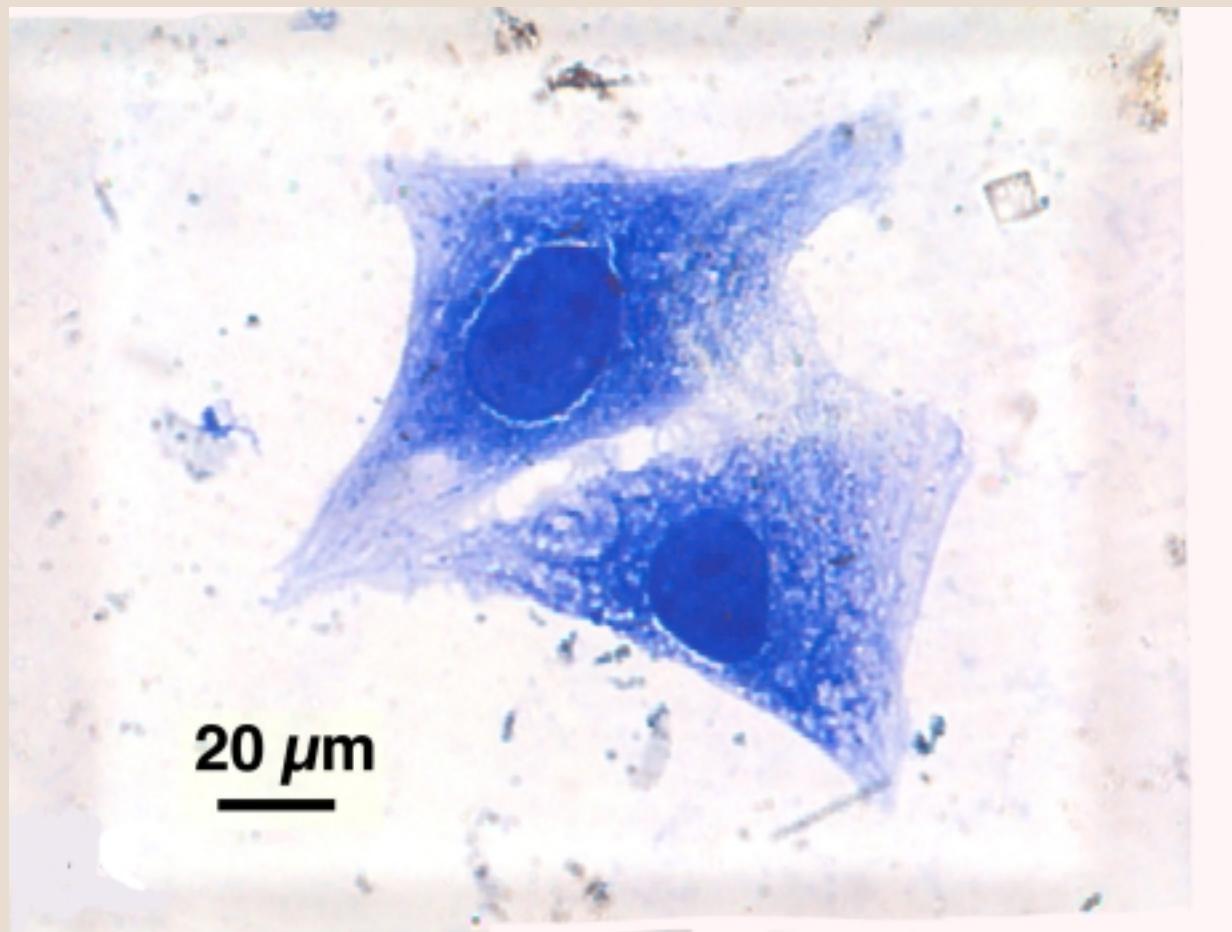
- Connecting morphology to damage mechanisms
- Need work on ionization mechanisms

Morphology

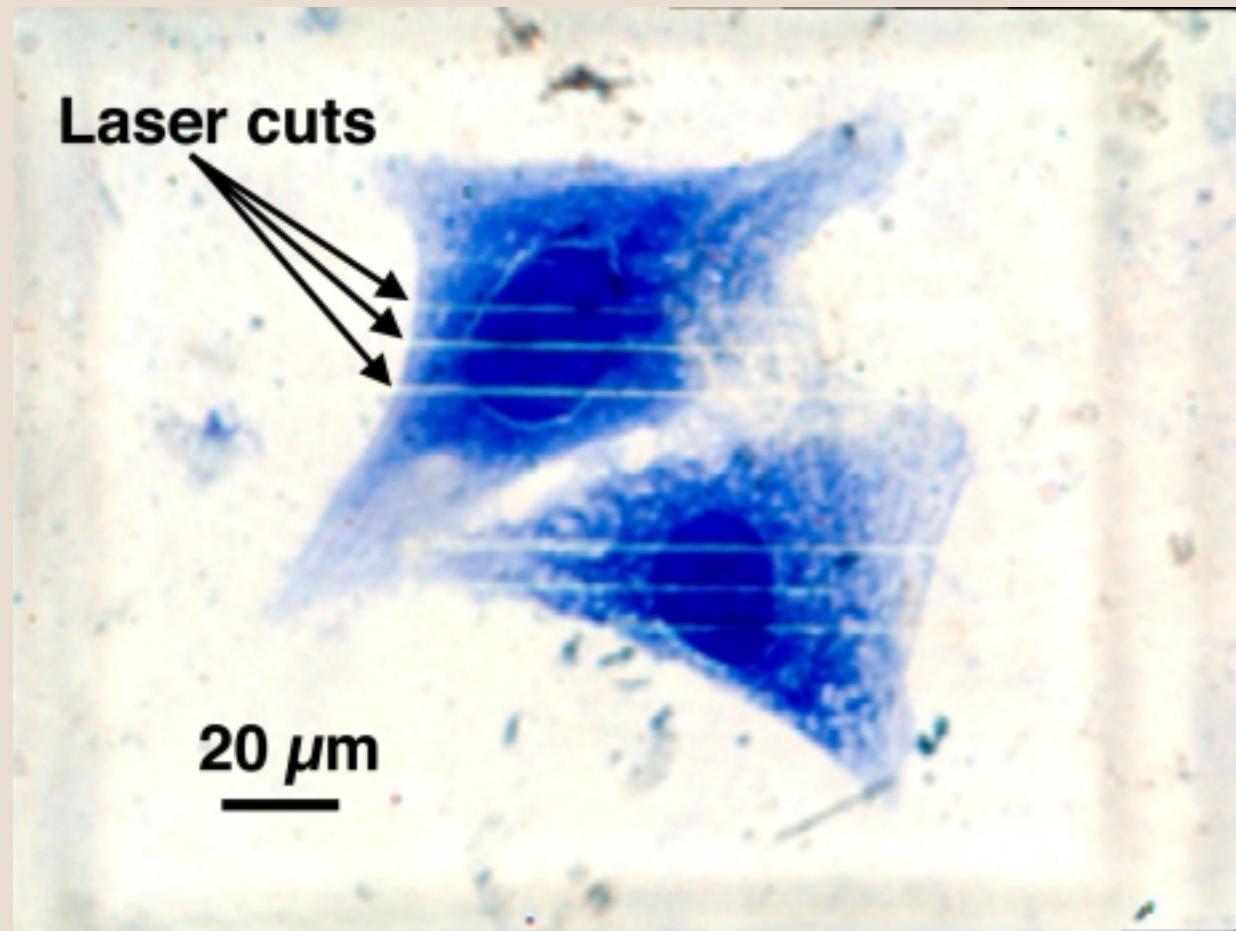
- Connecting morphology to damage mechanisms
- Need work on ionization mechanisms

Oscillator-only micromachining

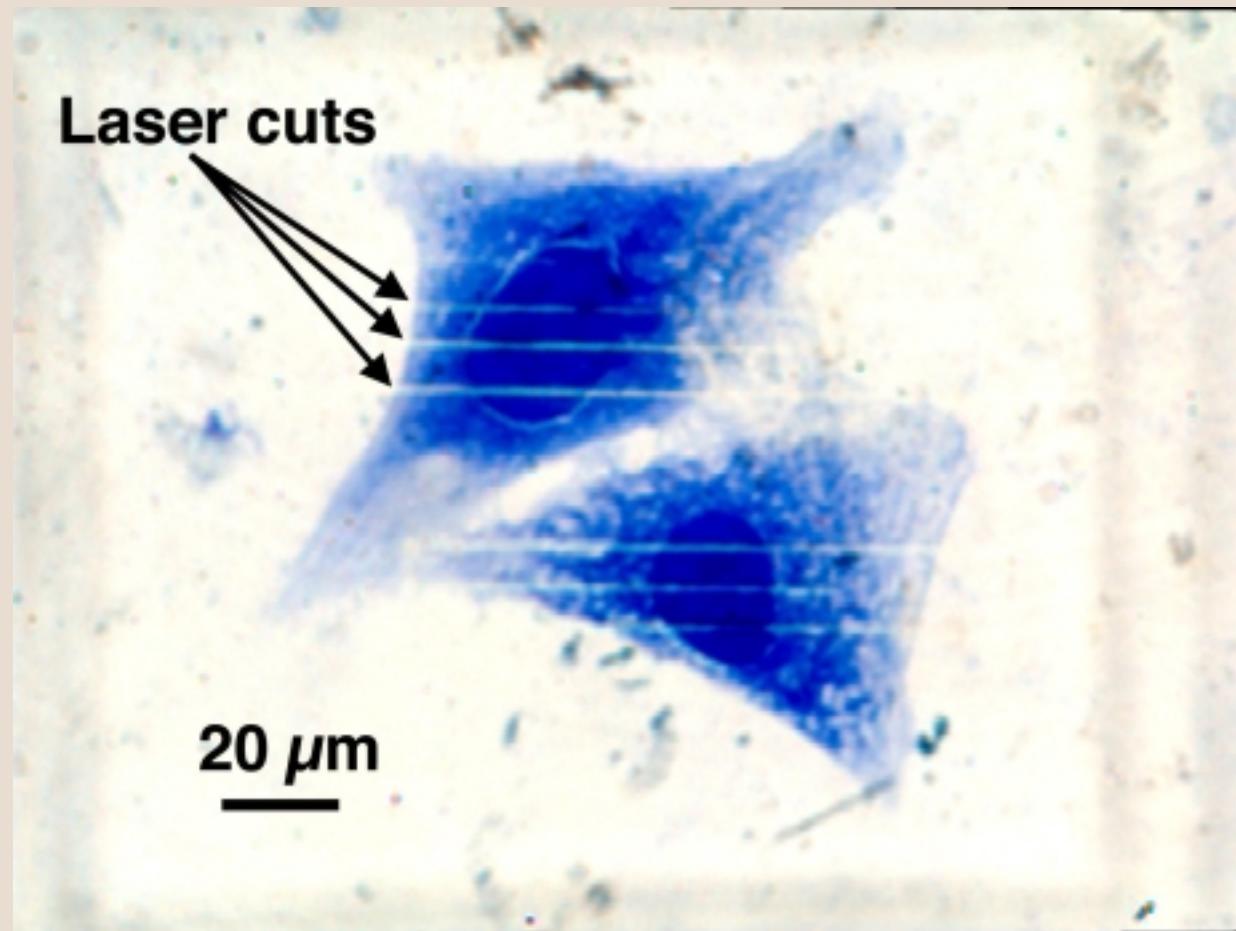
- Combining thermal and single-shot micromachining, we hope to create a variety of photonic structures using only a femtosecond laser oscillator.



bovine epithelial cells



after irradiation with 10-nJ pulses



sub-cellular surgical precision!

ACKNOWLEDGEMENTS

**W. Leight and N. Shen
Prof. N. Bloembergen**

National Science Foundation

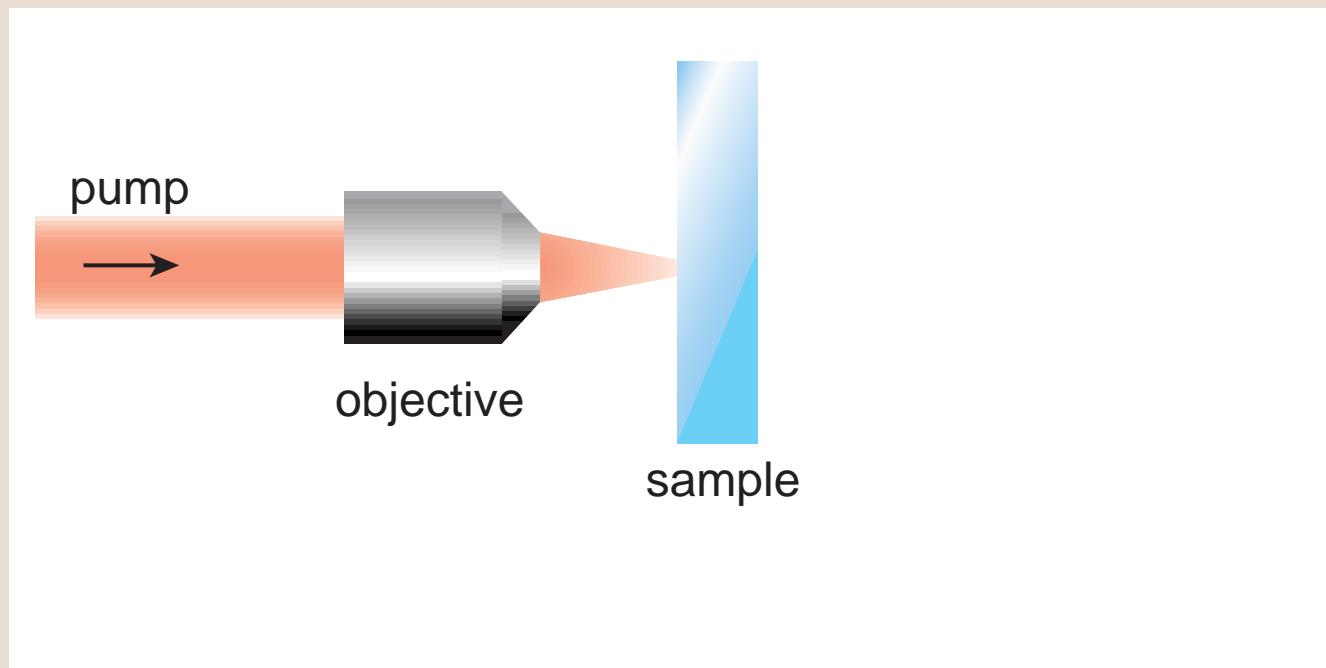
**For a copy of this talk and
additional information, see:**

<http://mazur-www.harvard.edu/>

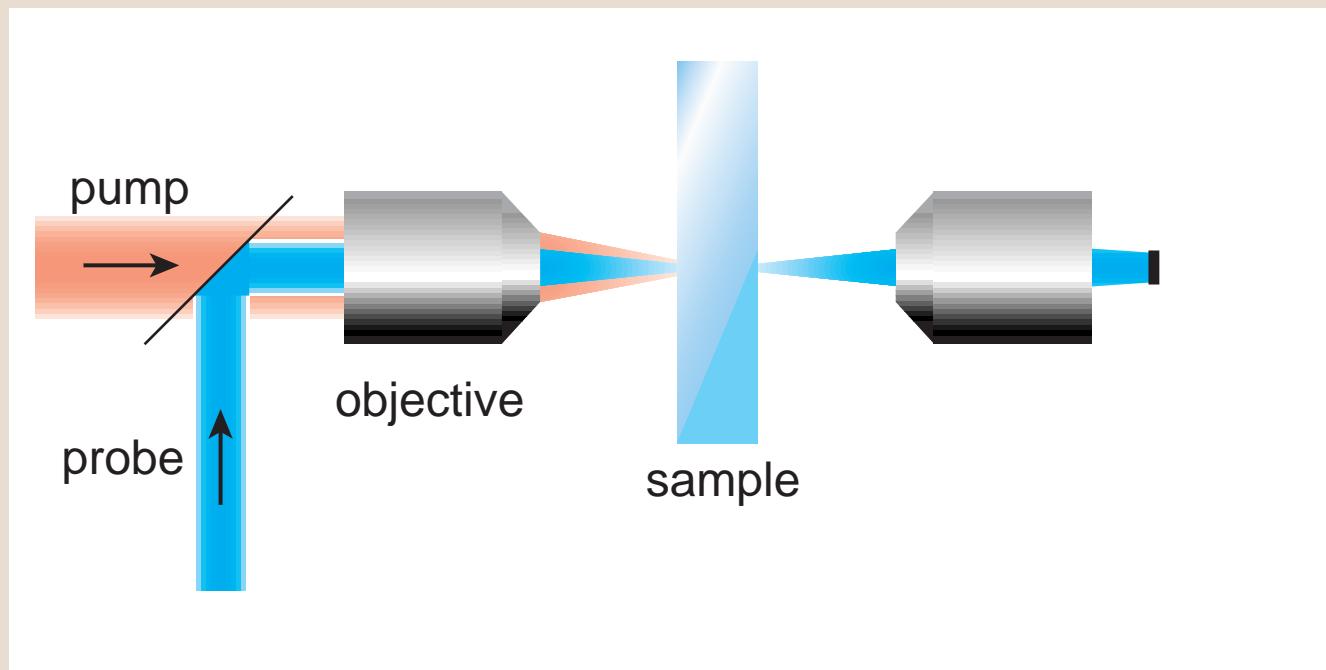
THRESHOLDS

**how little energy produces
permanent changes?**

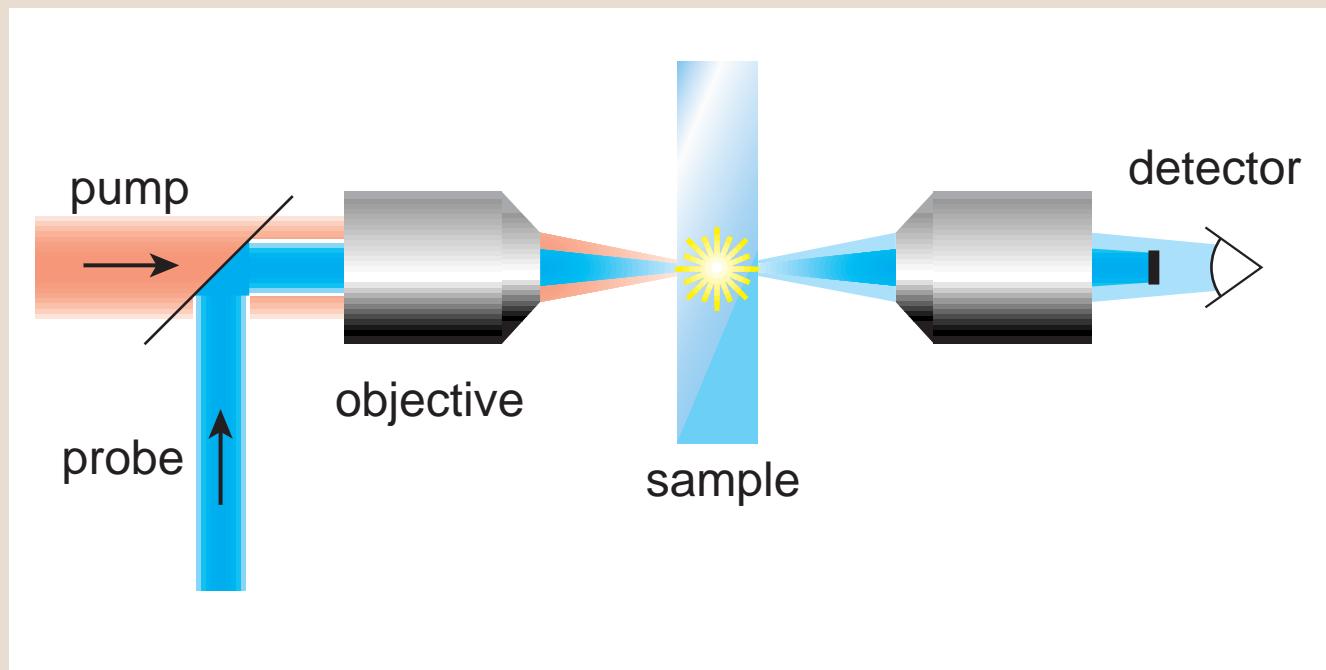
pump sample with femtosecond pulse



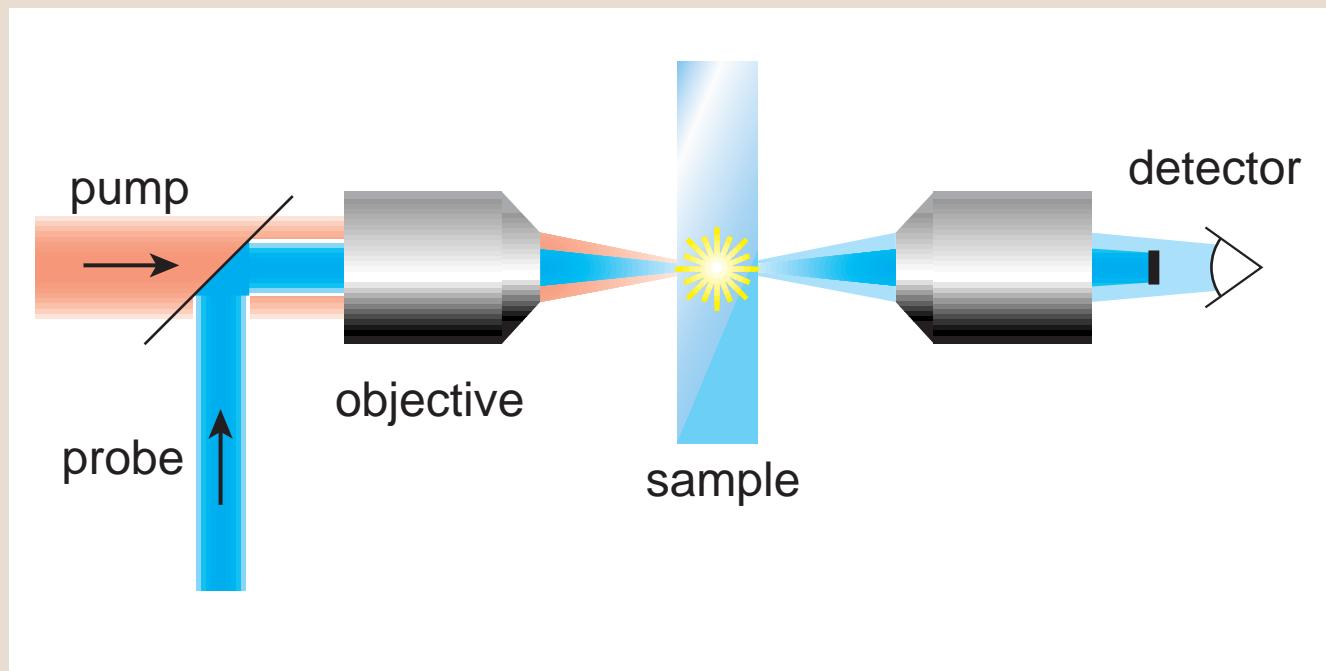
block probe beam



detect light scattered by damage

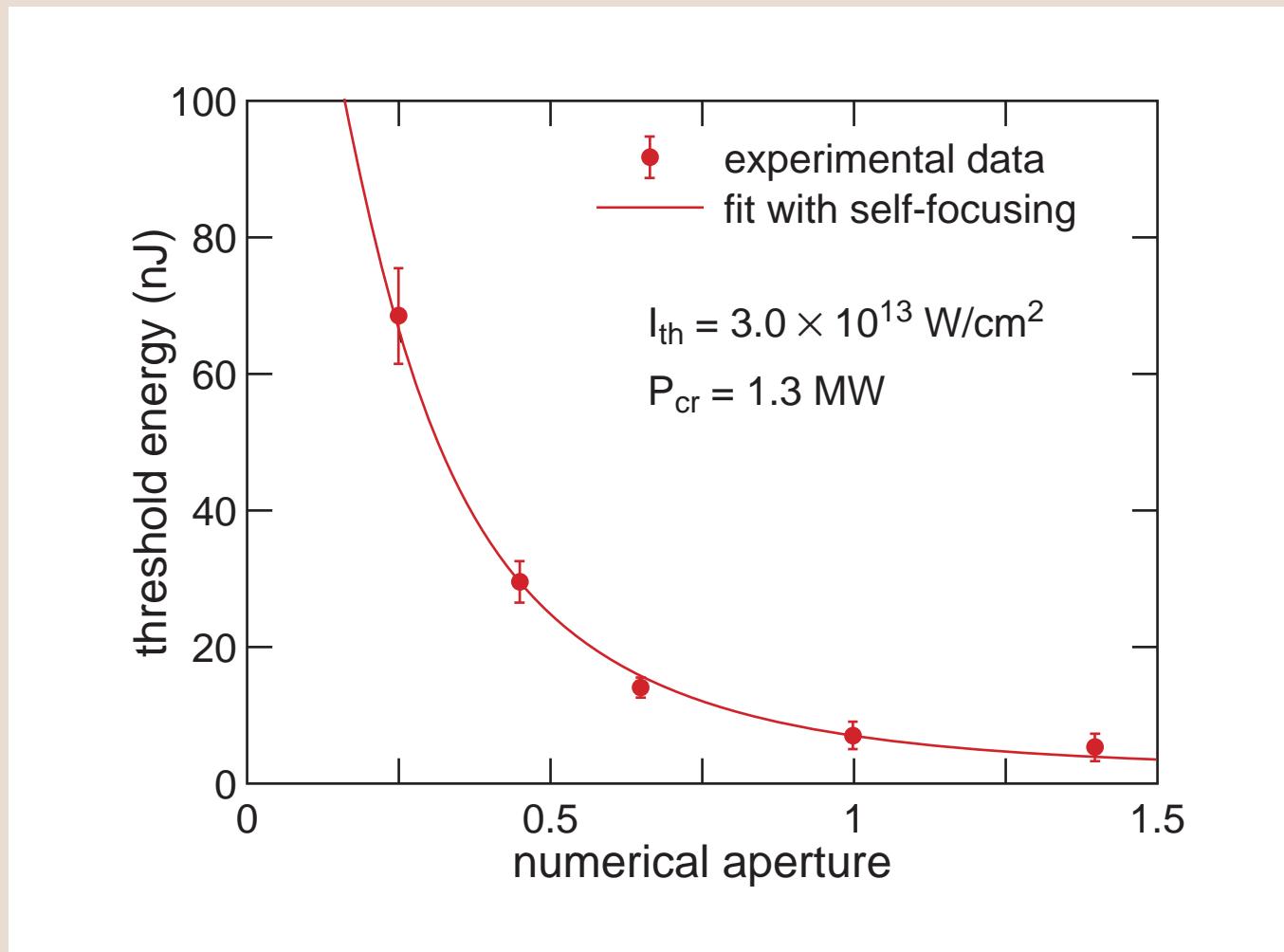


THRESHOLDS



vary NA, material, pump wavelength

THRESHOLDS



energy threshold vs. NA for 100-fs pulses in Corning 0211